



# Applications in Particle Physics



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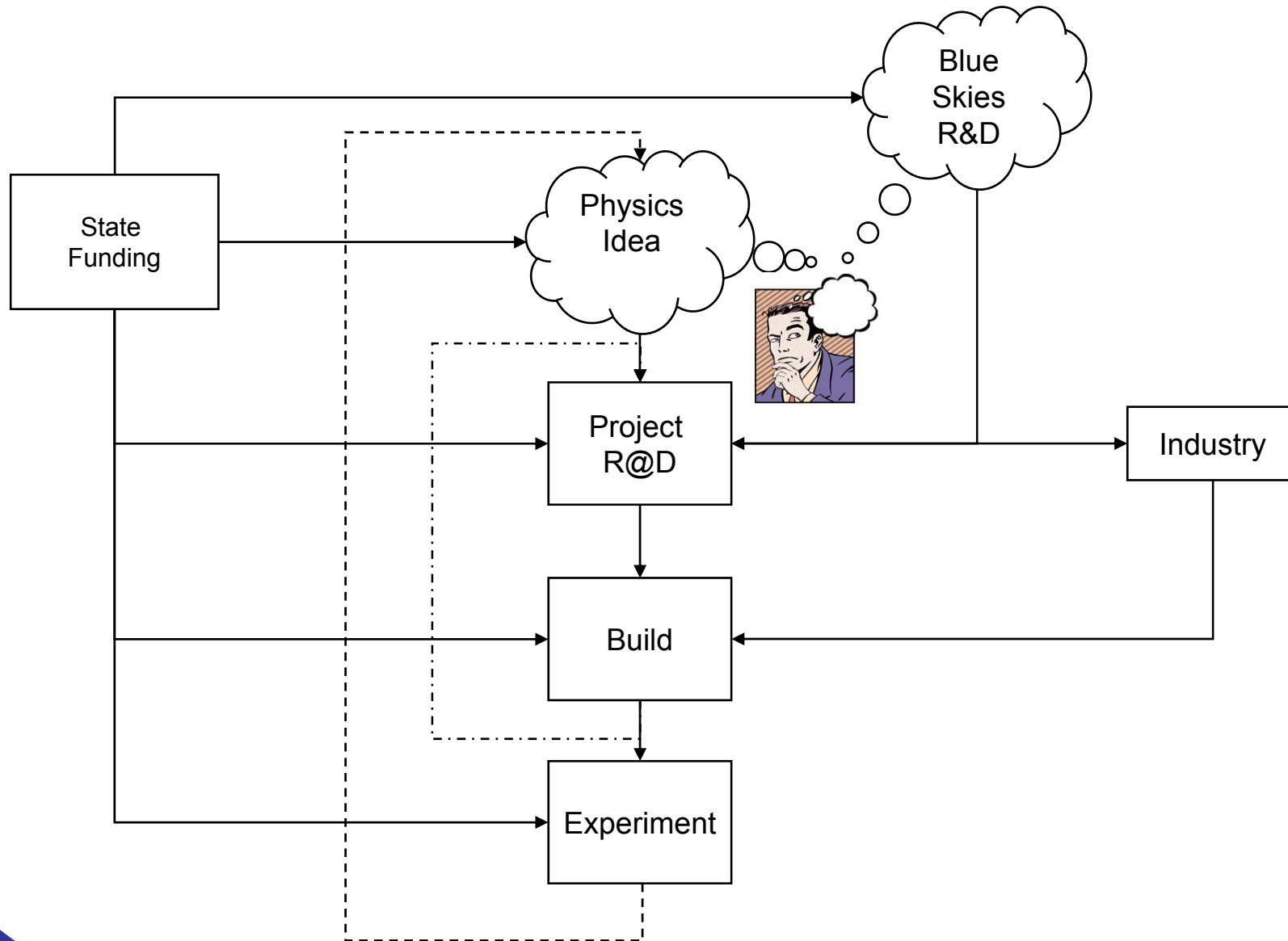
# Introduction

- Concentrate on applications
  - Many new ideas in other session
  - Active R&D for an experiments
- Do not attempt to produce exhaustive list
  - So much exciting work happening
  - Heavy dependence on electronics
- Flavour of some issues...
  - Highly personal

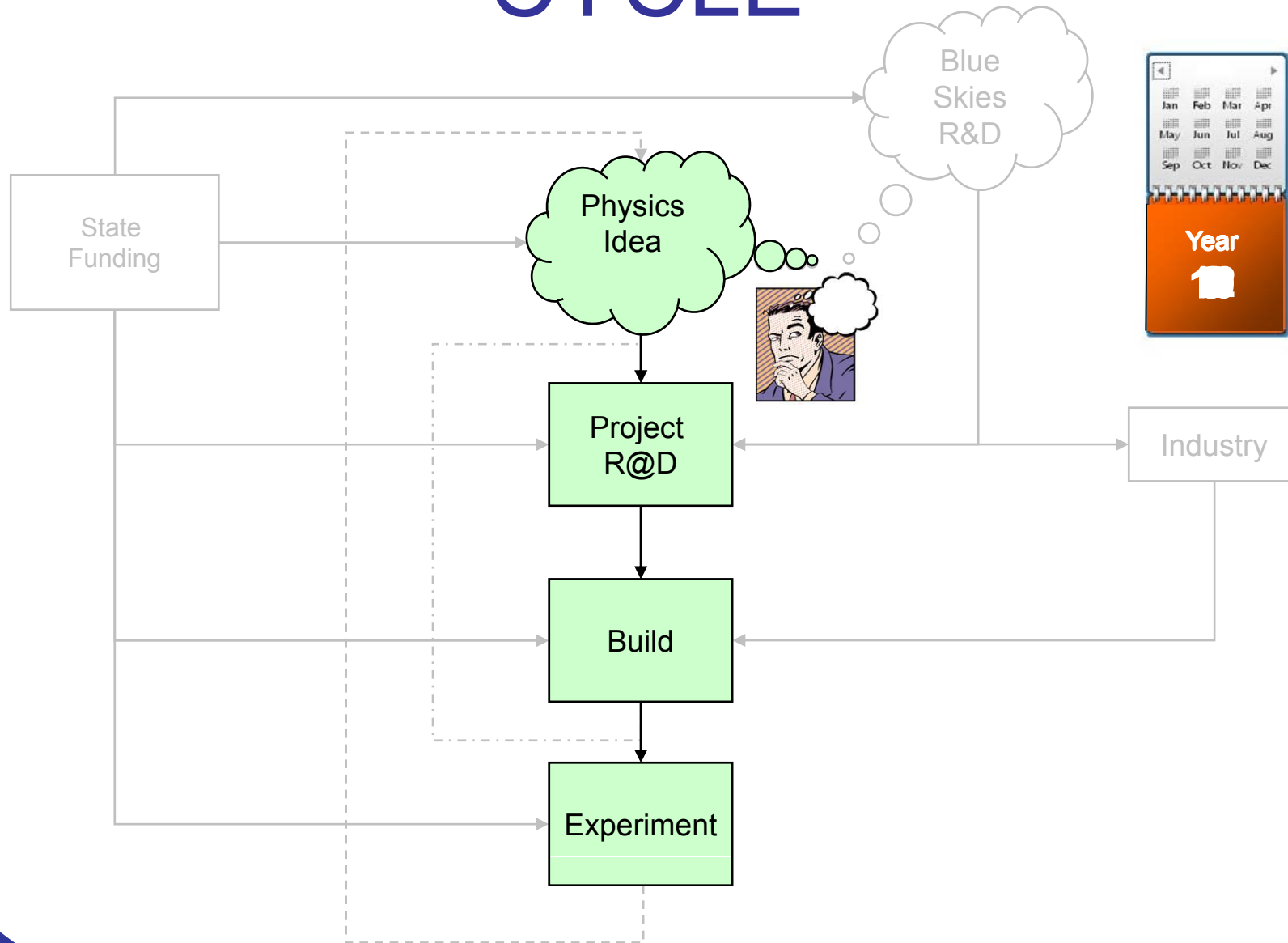
Funding Agencies

Universities & Labs

Private Sector

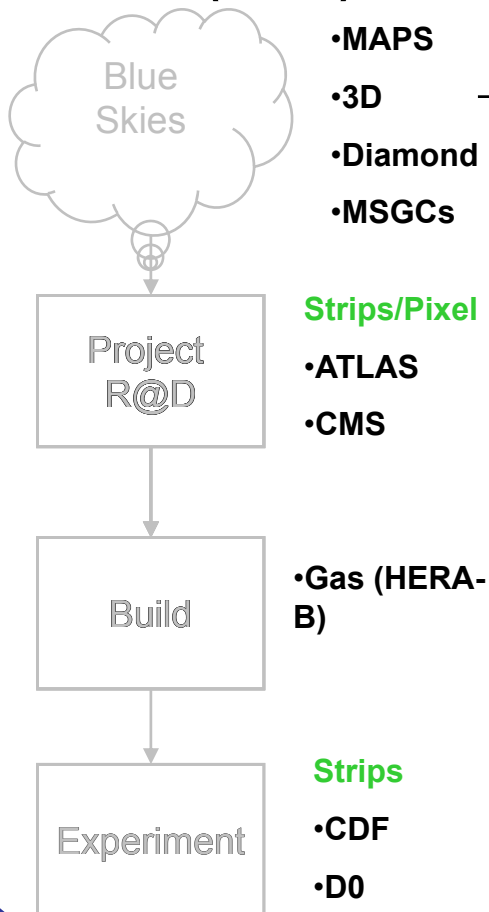


# CYCLE

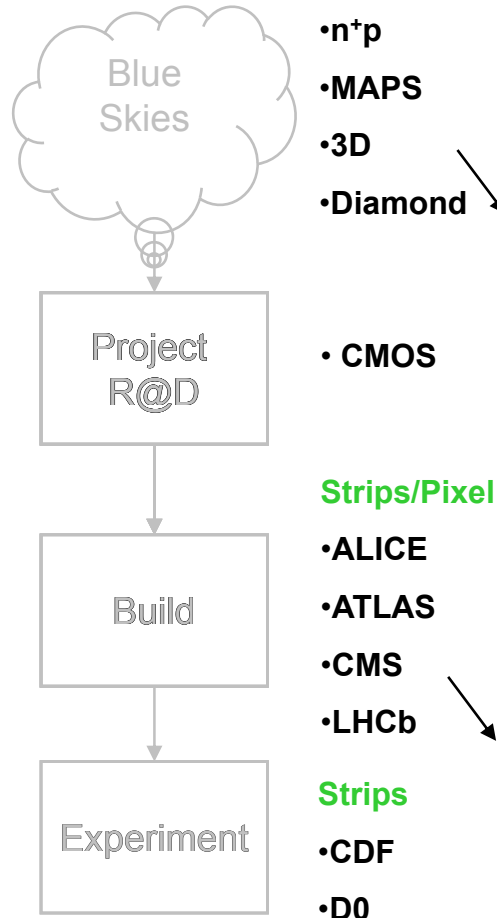


# History

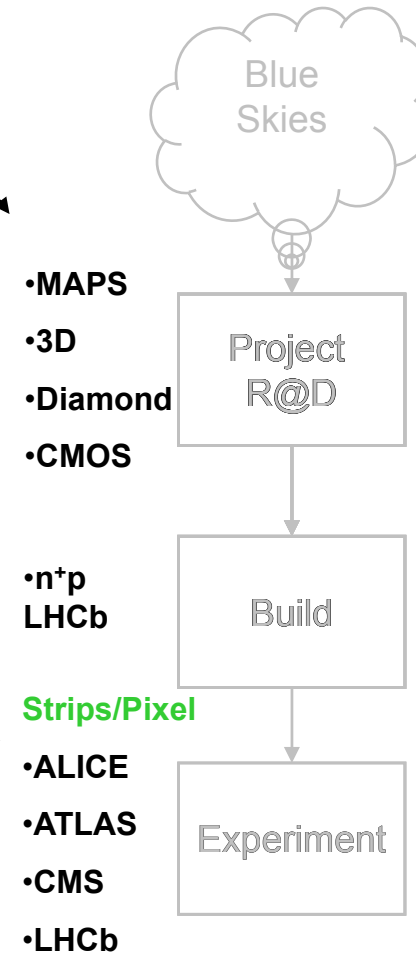
## PSD VI (2003)



## PSD VII (2005)



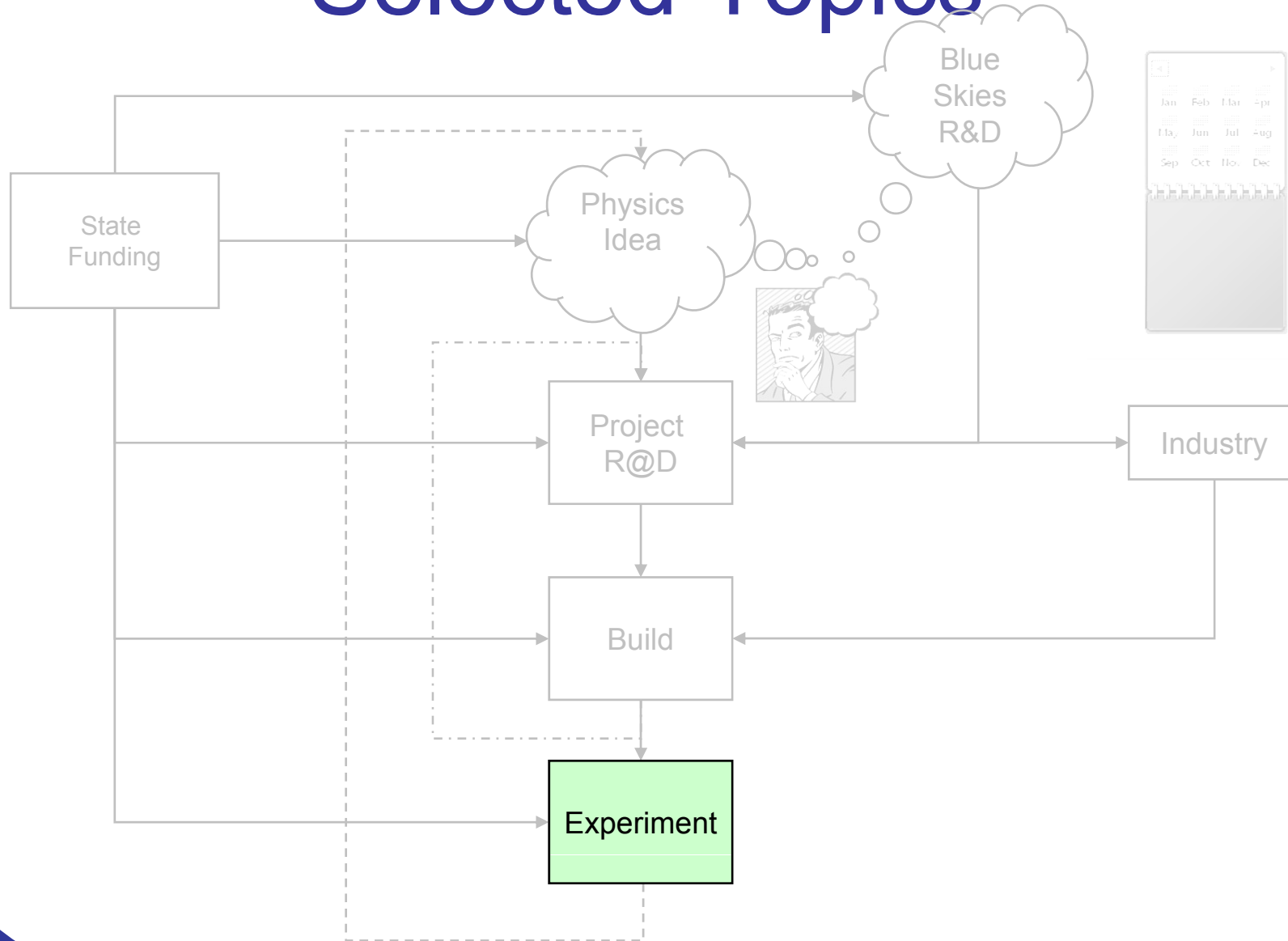
## PSD VIII (2008)



# Particle Physics - Last 5 years

- Increasing concentration on solid state detectors
  - In PP less gas
- More emphasis on pixels (over strips)
  - strips → engineering issues
- Progress on radiation hard Si
- Maturing of many technologies
  - Diamond
- Large progress
  - CMOS

# Selected Topics



# News from LHC

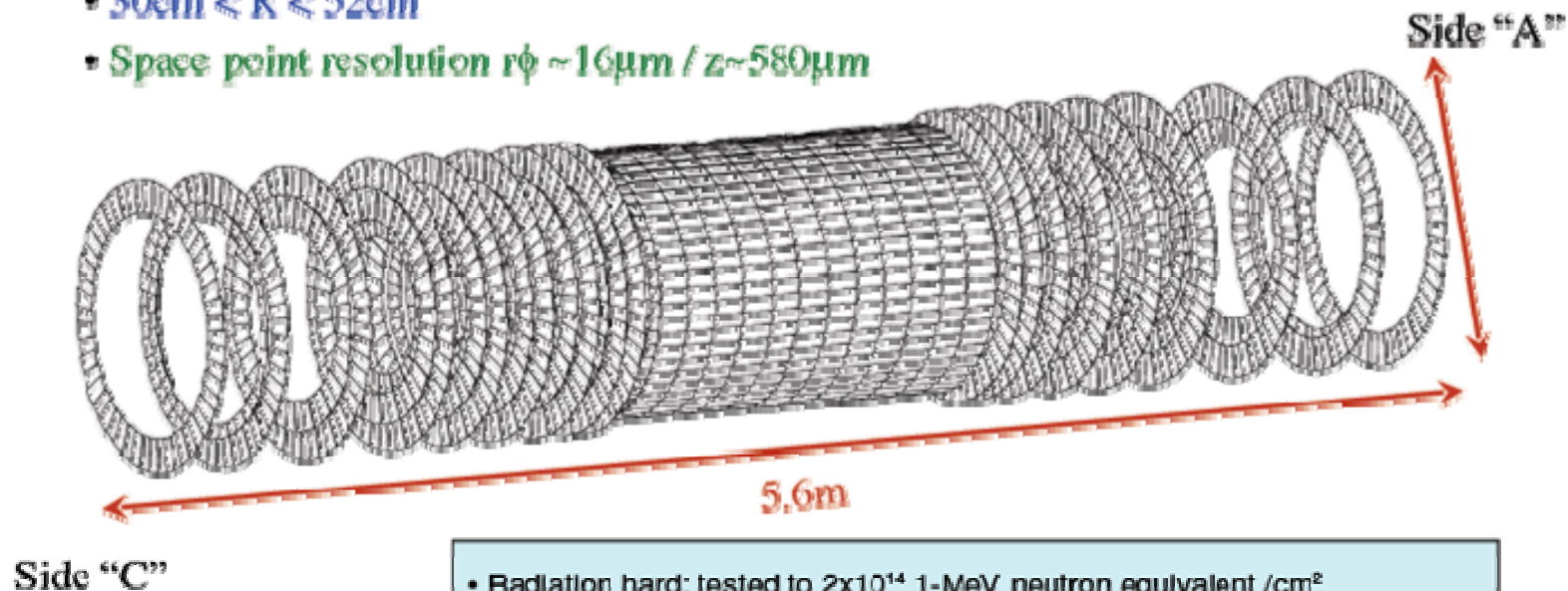
- PSD's figure highly in recent developments (see Chris Parkes' talk on opening day)
- Commissioning
  - Cosmic Rays
  - Synchronization tests
  - Building up to circulating beam (10<sup>th</sup> Sept)



# ATLAS

## Atlas SemiConductor Tracker in numbers:

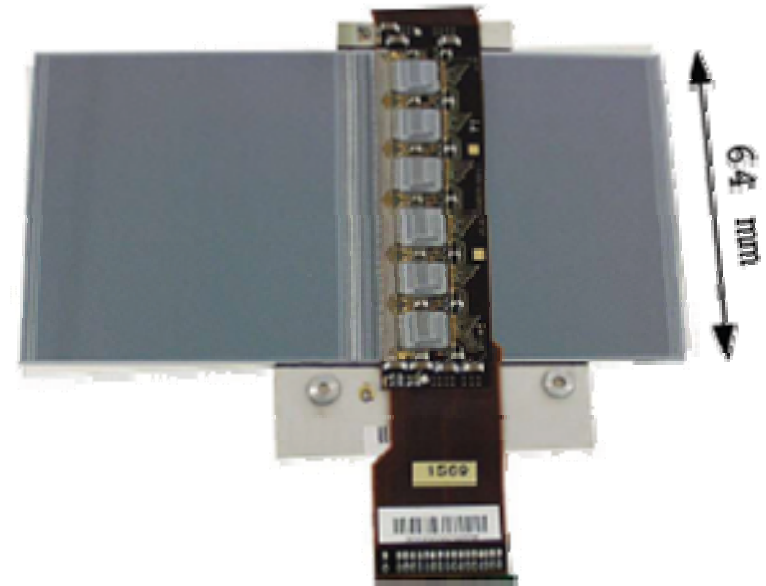
- 61 m<sup>2</sup> of silicon, 6.2 million readout channels
- 4088 silicon modules, arranged to form 4 Barrel layers and 18 Disks (9 each end)
- Barrel : 2112 modules (1 type) giving coverage  $|\eta| < 1.1$  to 1.4
- End-caps : 1976 modules (4 types) with coverage  $1.1 < |\eta| < 2.5$
- $30\text{cm} \leq R \leq 52\text{cm}$
- Space point resolution  $r\phi \sim 16\mu\text{m} / z \sim 580\mu\text{m}$



- Radiation hard: tested to  $2 \times 10^{14}$  1-MeV neutron equivalent /cm<sup>2</sup>
- Lightweight: 3% X0 per layer
- Global collaboration by 32 institutes

# ATLAS MODULES

- Single-sided  $p$ -implanted strips on  $n$ -type  $Si$
- Back-to-back sensors, glued to highly thermally conductive substrates for mechanical/thermal stability
- 40mrad stereo angle between sensors
- 1536 channels (768 on each side), 6 chips/side
- Binary readout
- Optical communication to DAQ
- 5.6W/module (rising to  $\sim 10$ W after 10 years LHC)
- up to 500V sensor bias
- Cooled to  $-8^{\circ}\text{C}$  to limit sensor radiation damage



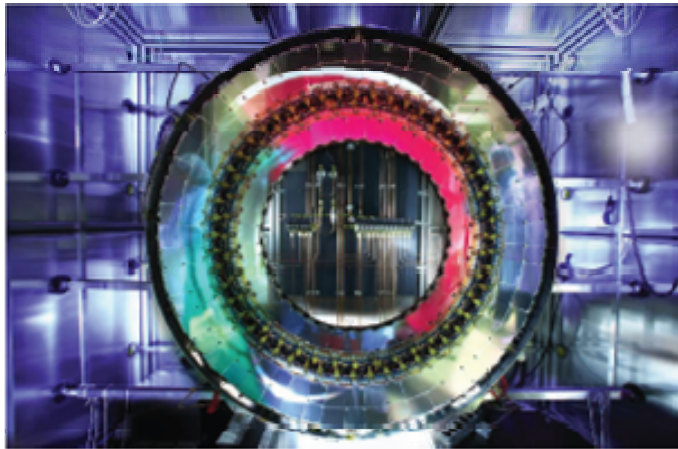
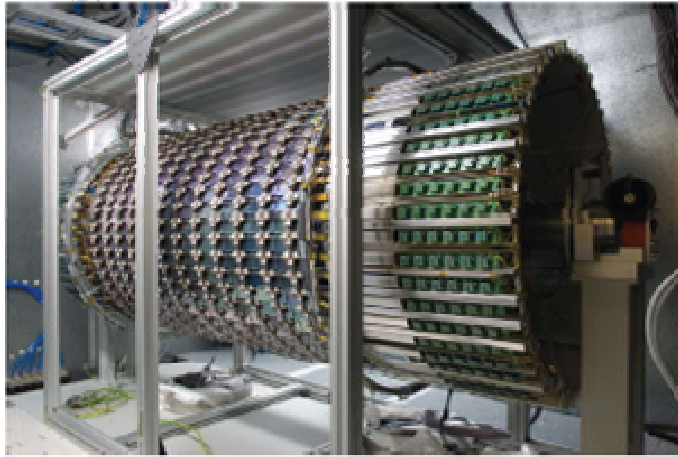
- 2112 barrel modules
- one shape
- assembled at 4 SCT sites



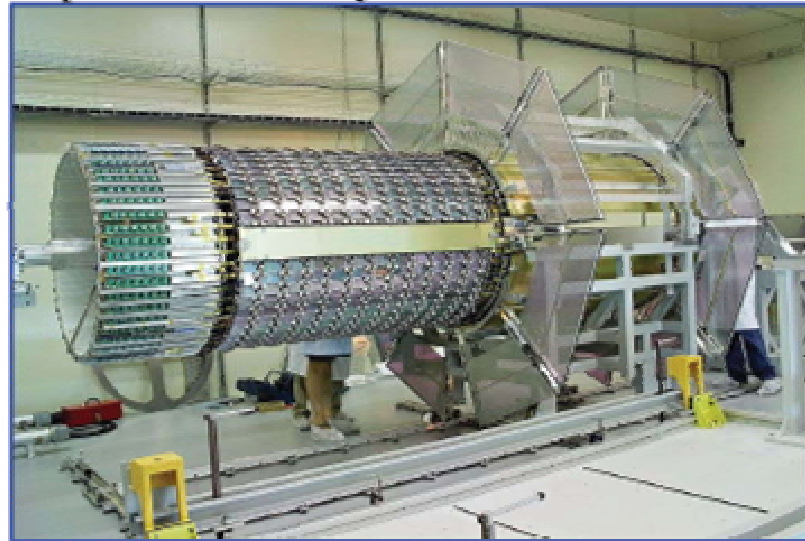
- 1976 endcap modules
- 3 shapes
- assembled at 7 SCT sites

# ATLAS

Single cylinder tests



Sept. 2005: outer layer in thermal enclosure

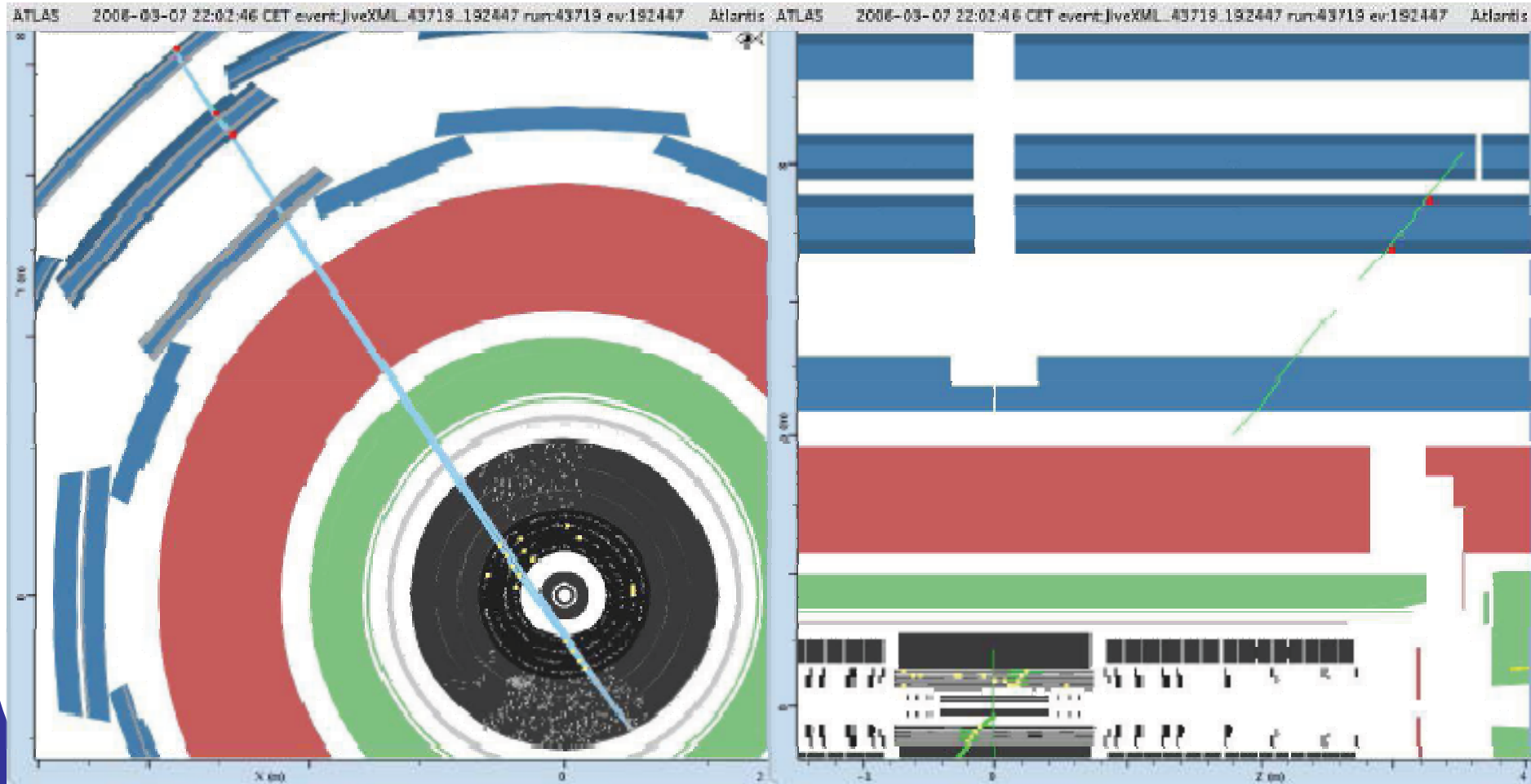


Dec. 2006: inner layer insertion



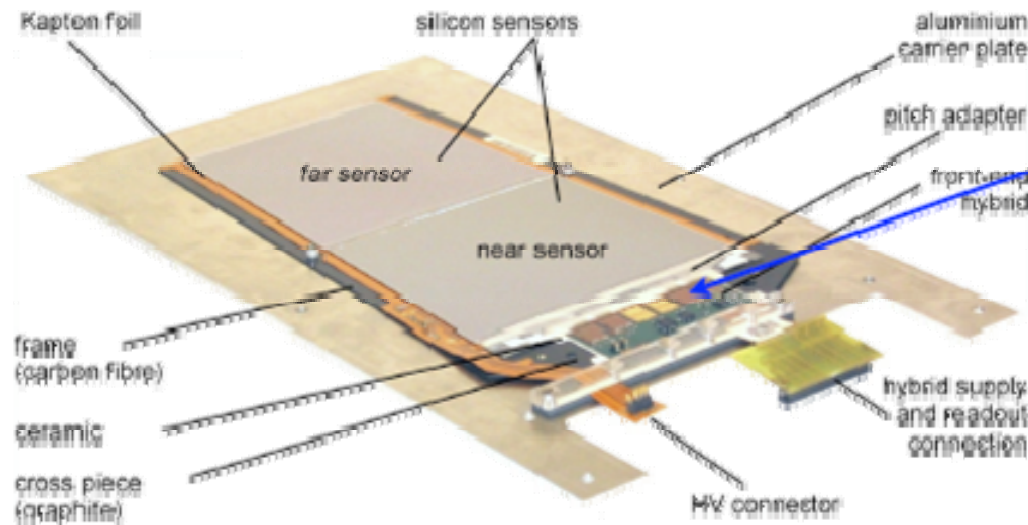
Themis Bowcock

# LHC Experiment Commissioning



Early 2008:Cosmics observed  
in all LHC experiments

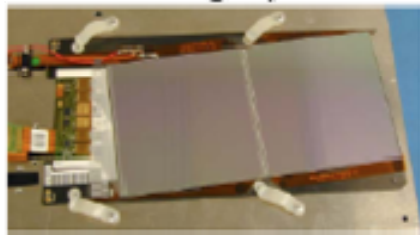
# CMS modules



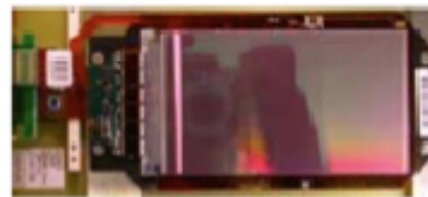
Each module includes analogue readout chips (APV25)

27 different types of modules

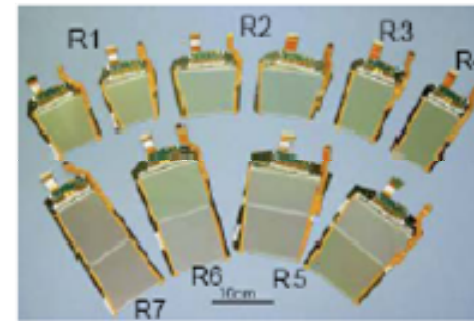
**TOB stereo module (100 mrad stereo angle)**



**TIB module**



**TID/TEC modules**



28th July 2008

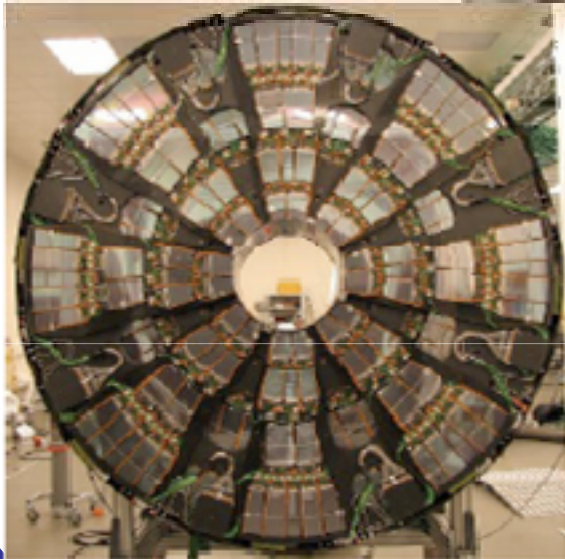
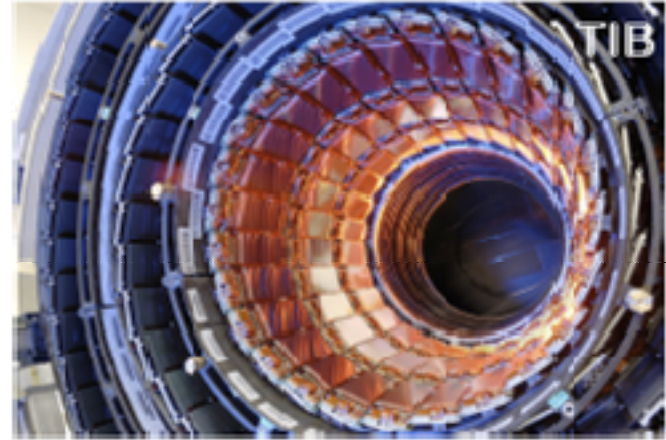
CMS Tracker Commissioning - VERTEX08 - Joanne Cole



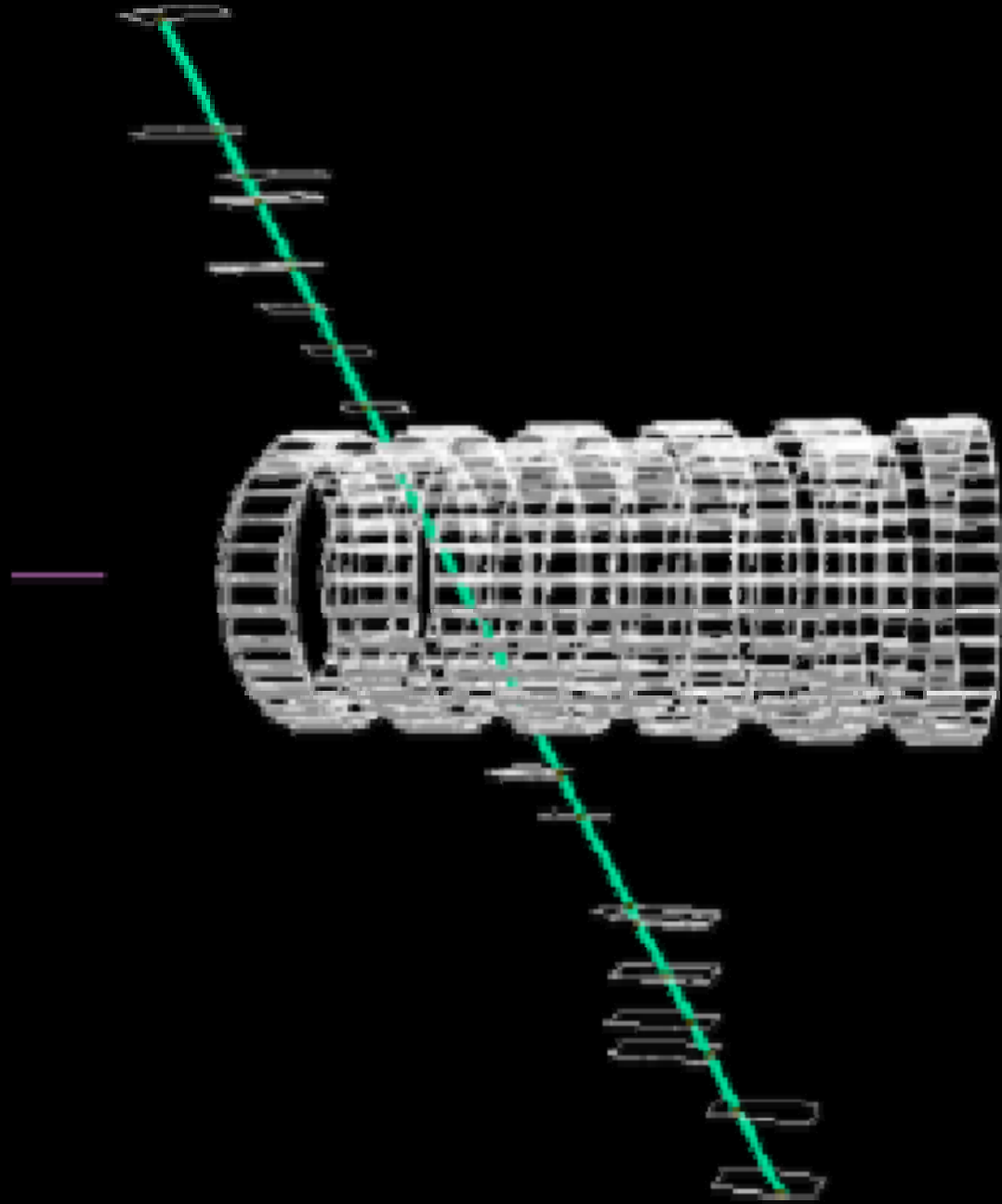
# CMS

TID →

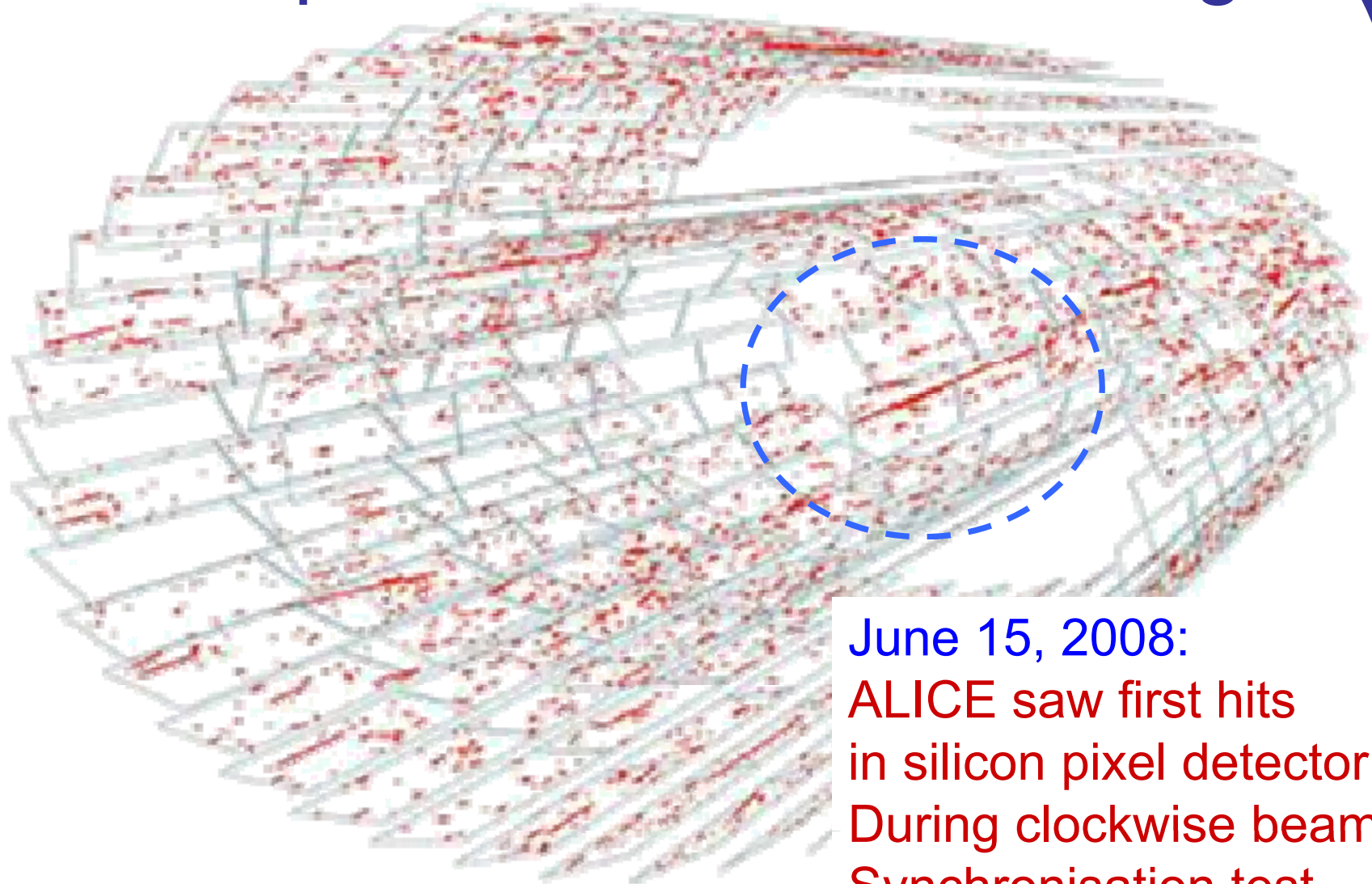
↓ TEC



# CMS

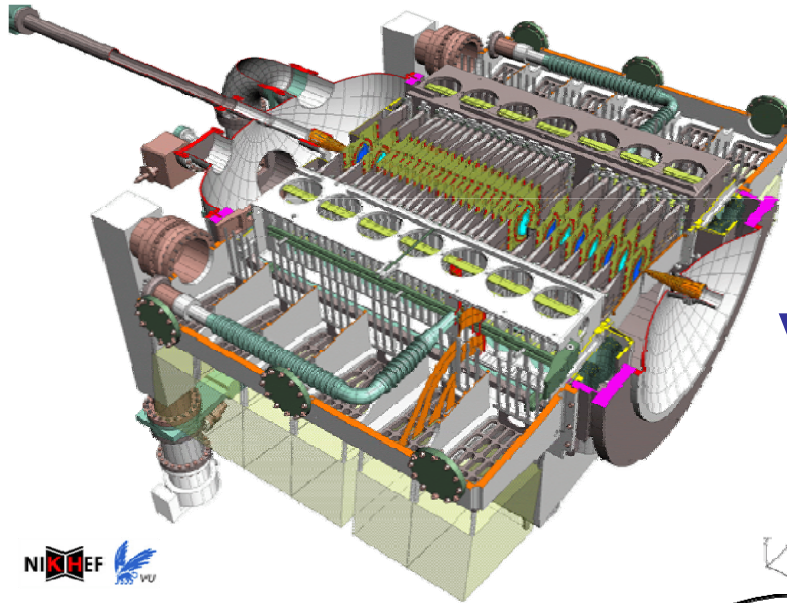


# LHC Experiment Commissioning

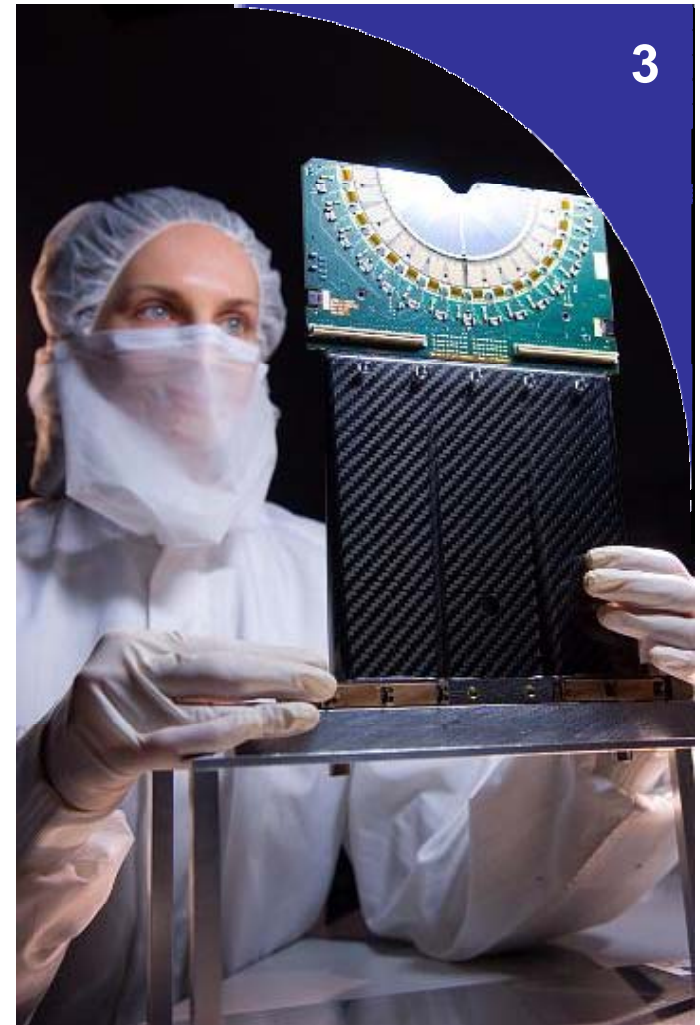
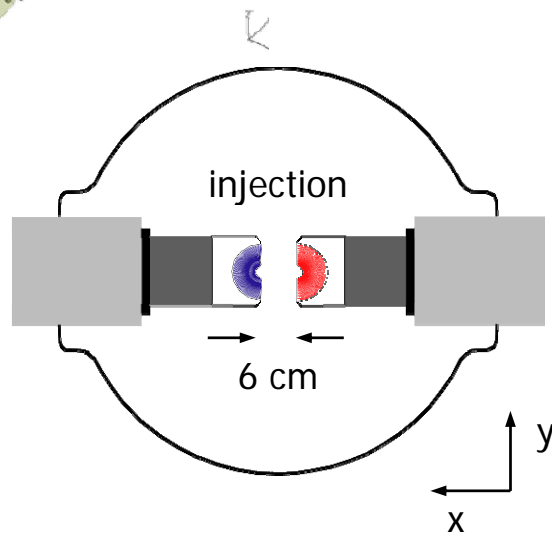


June 15, 2008:  
ALICE saw first hits  
in silicon pixel detector  
During clockwise beam  
Synchronisation test

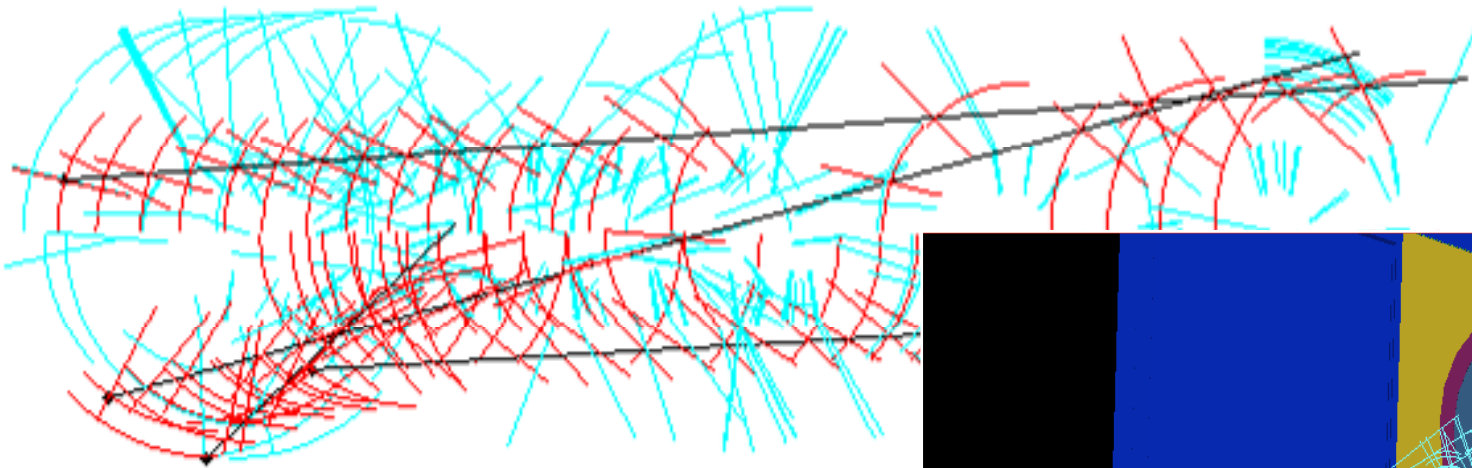




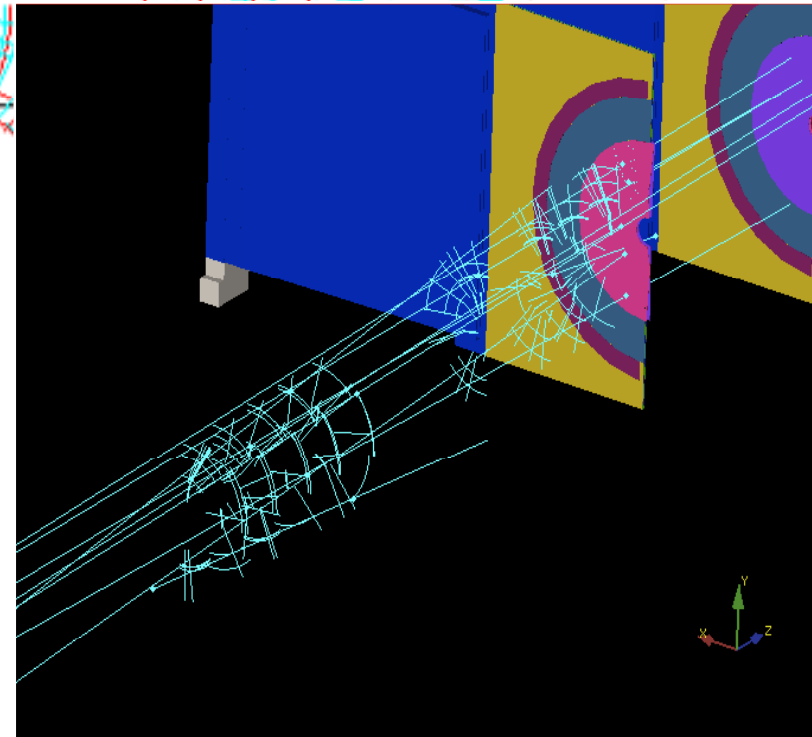
# VELO LHCb



# 22<sup>nd</sup> August



Reconstructed tracks!

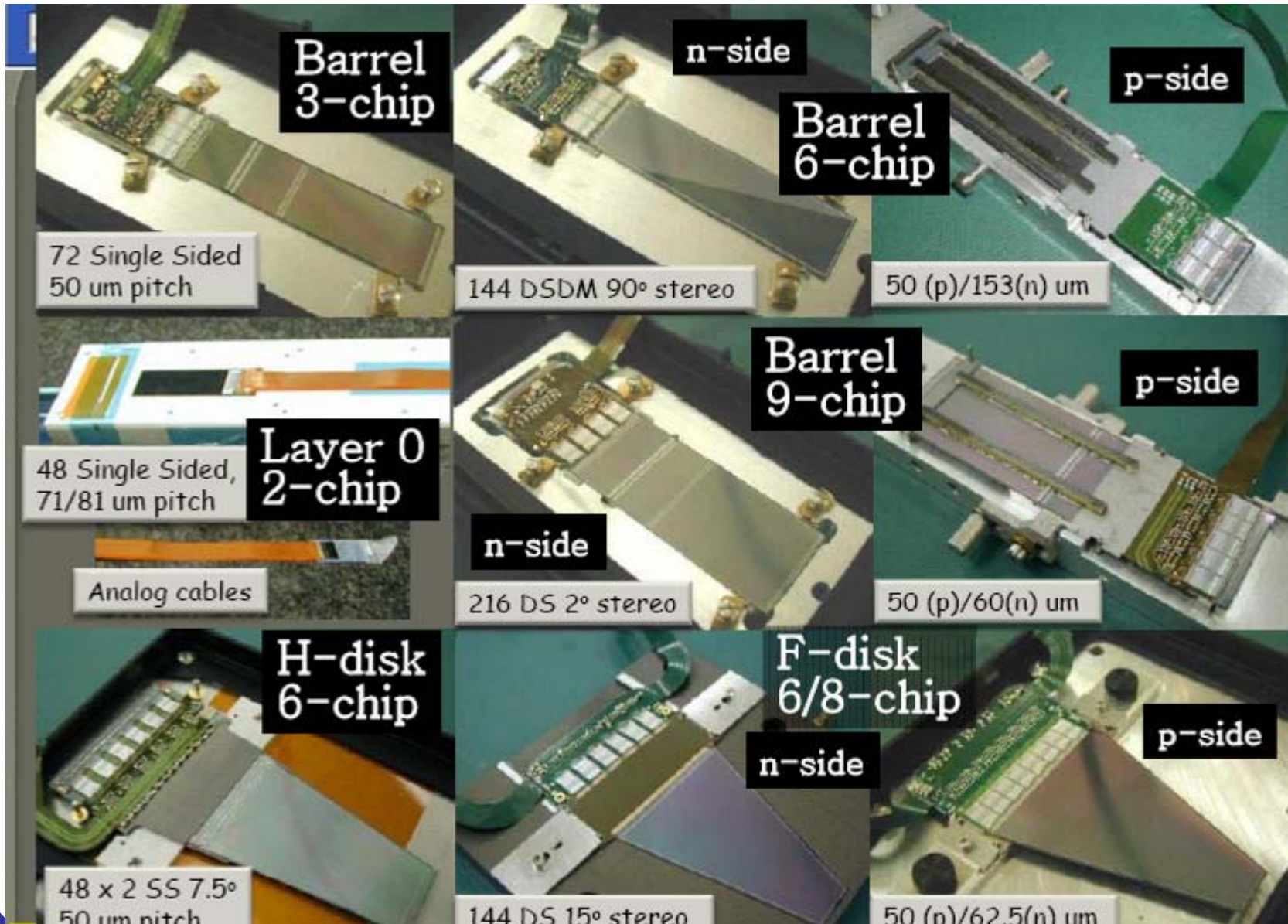


# In a few weeks...

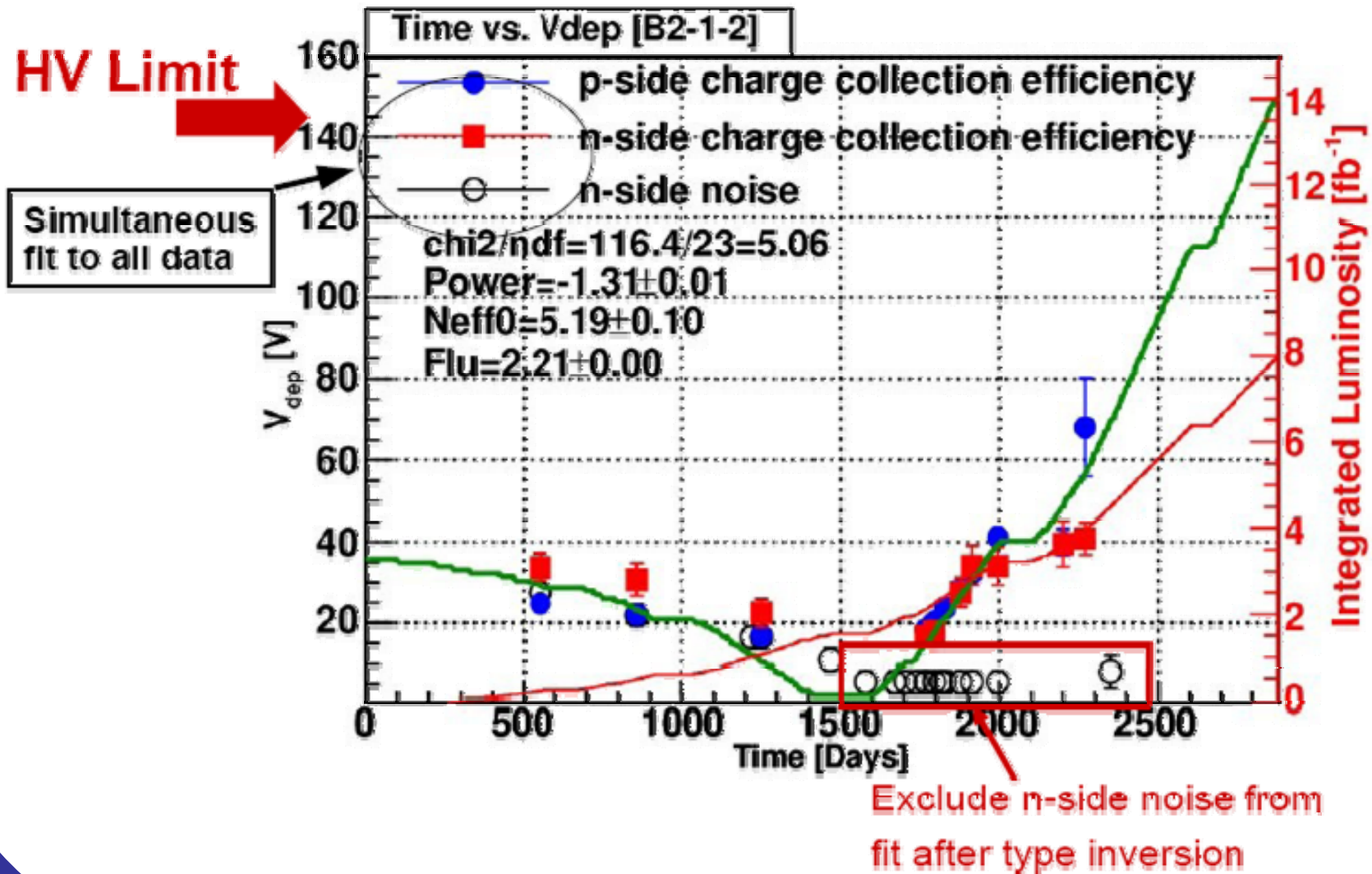
- Real tracks and vertices from the next generation of detectors (See the next PSD!)

# Other experiments

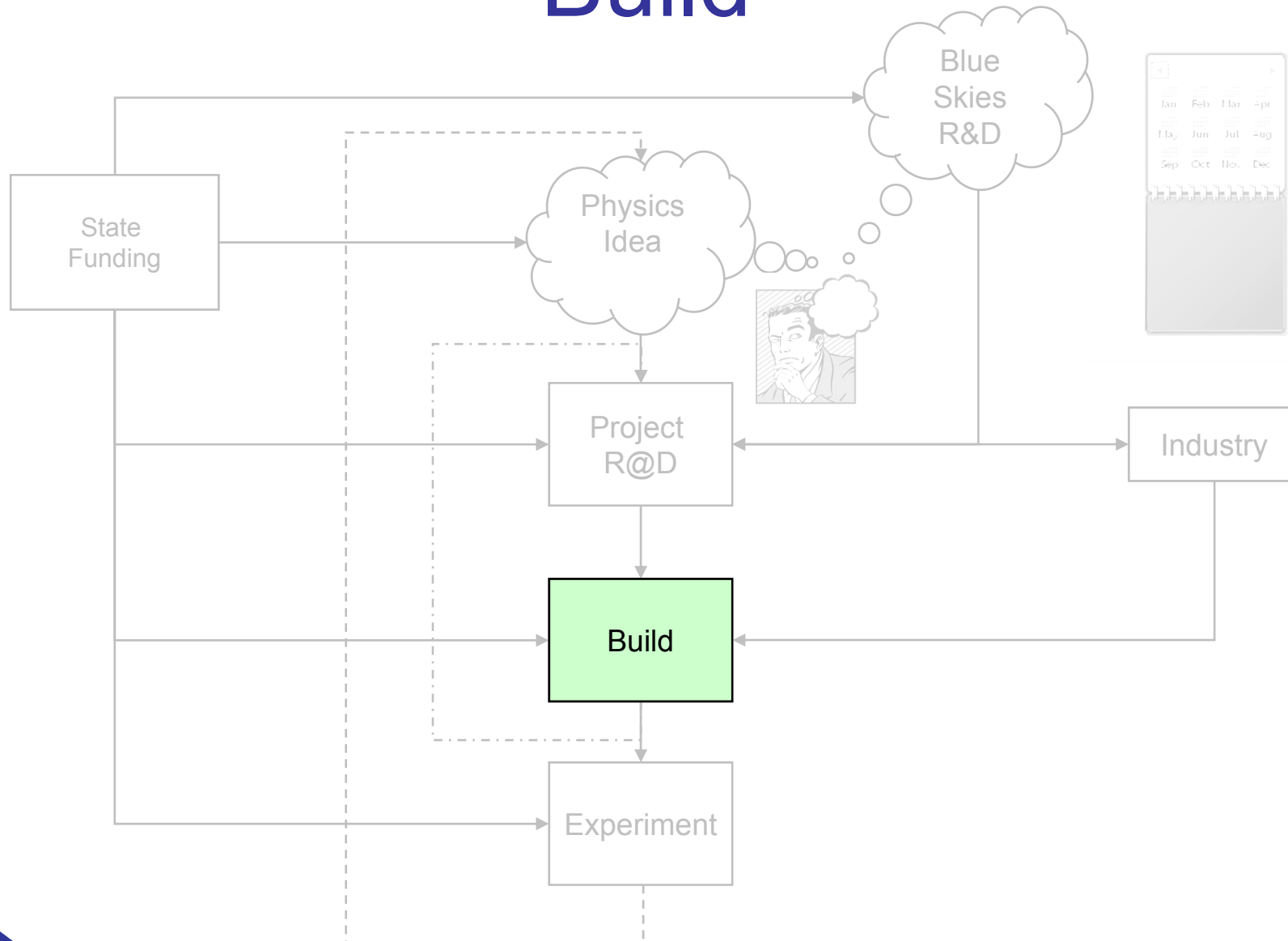
- D0



# Type Inversion



# Build

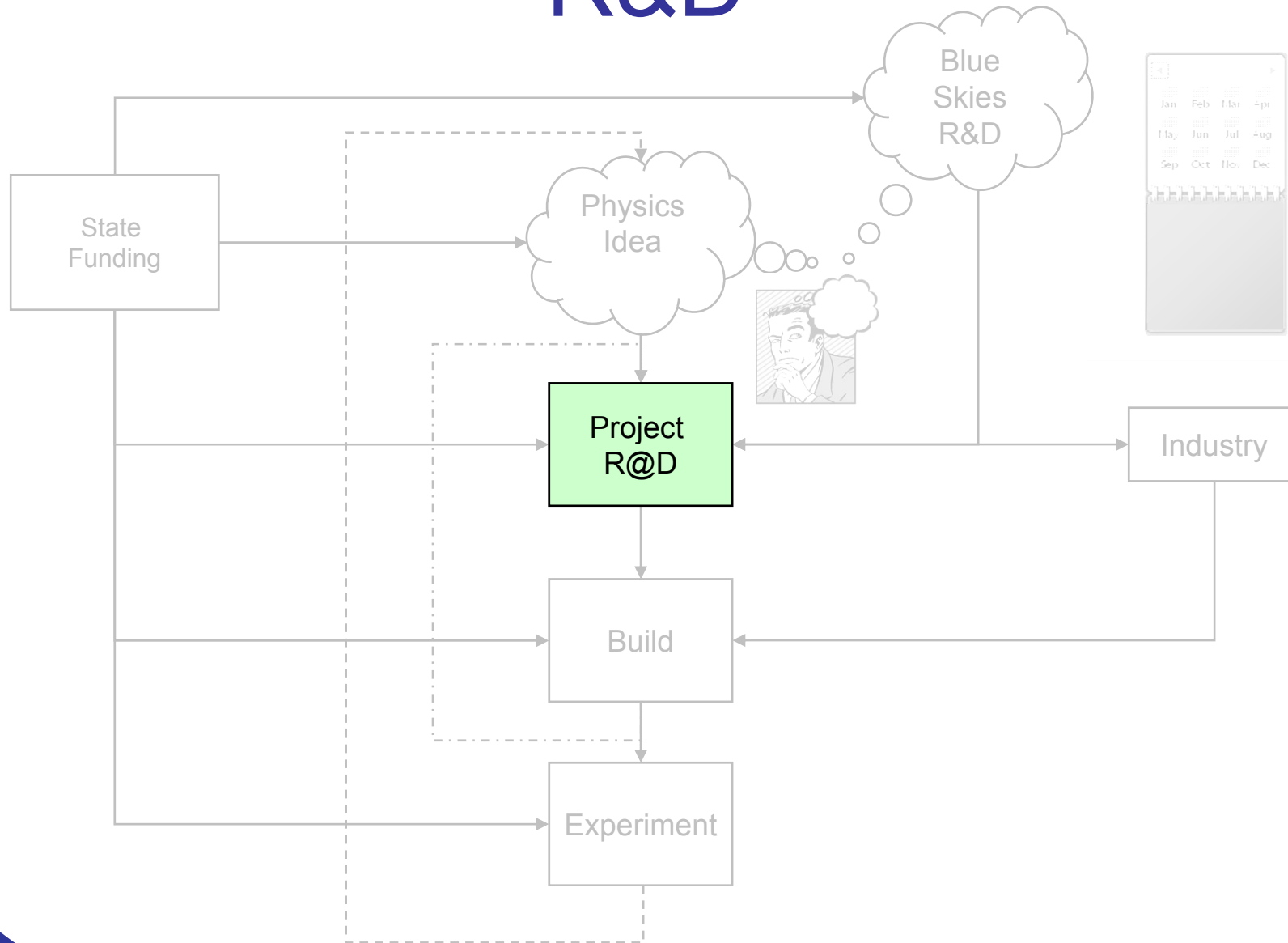


# Build

- The effort to get the CERN experiments ready dominated the last few years
  - A few builds still in progress
    - E.g. LHCb “spare” VELO using n<sup>+</sup>p technology

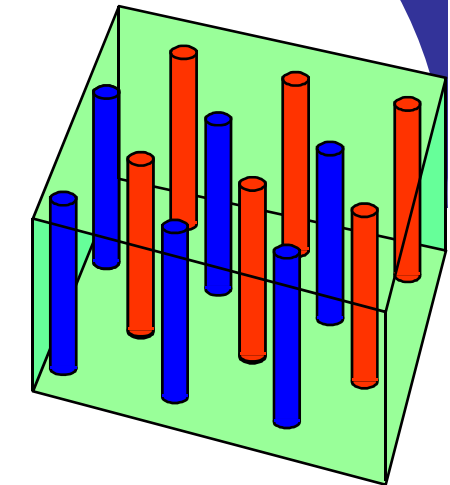


# R&D

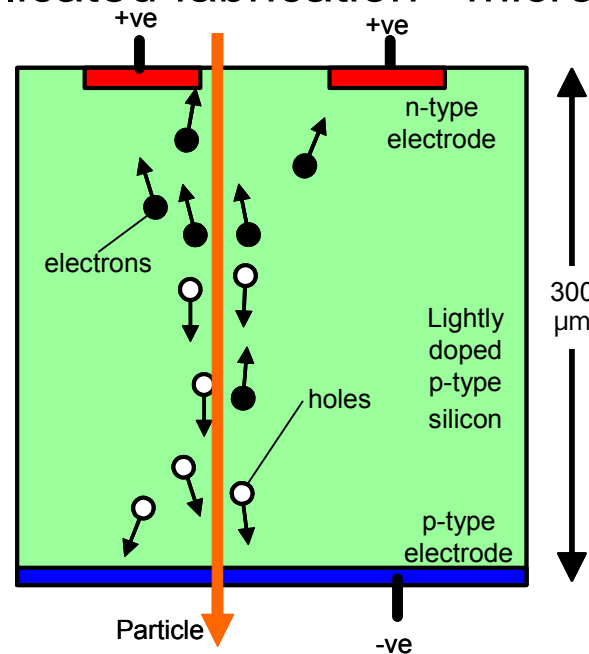


# 3D

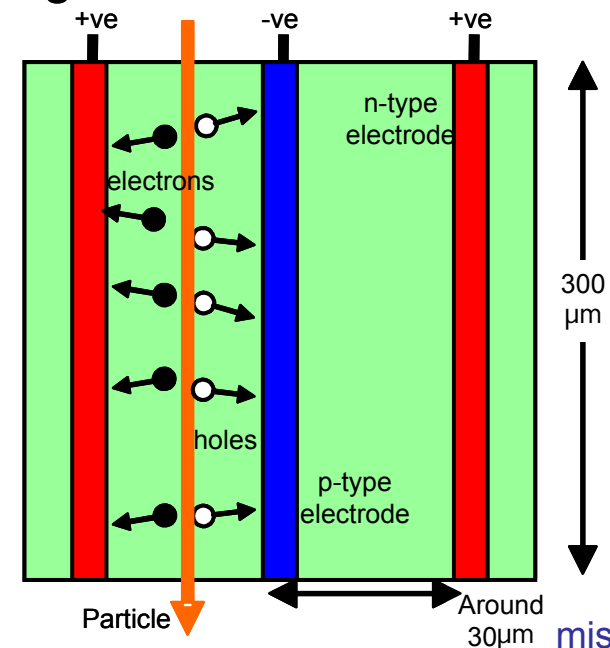
- Array of electrode columns passing through substrate
- Electrode spacing  $\ll$  wafer thickness (e.g.  $30\mu\text{m}:300\mu\text{m}$ )
- Benefits
  - $V_{\text{depletion}} \propto (\text{Electrode spacing})^2$
  - Collection time  $\propto$  Electrode spacing
  - Reduced charge sharing
- More complicated fabrication - micromachining



**Planar**

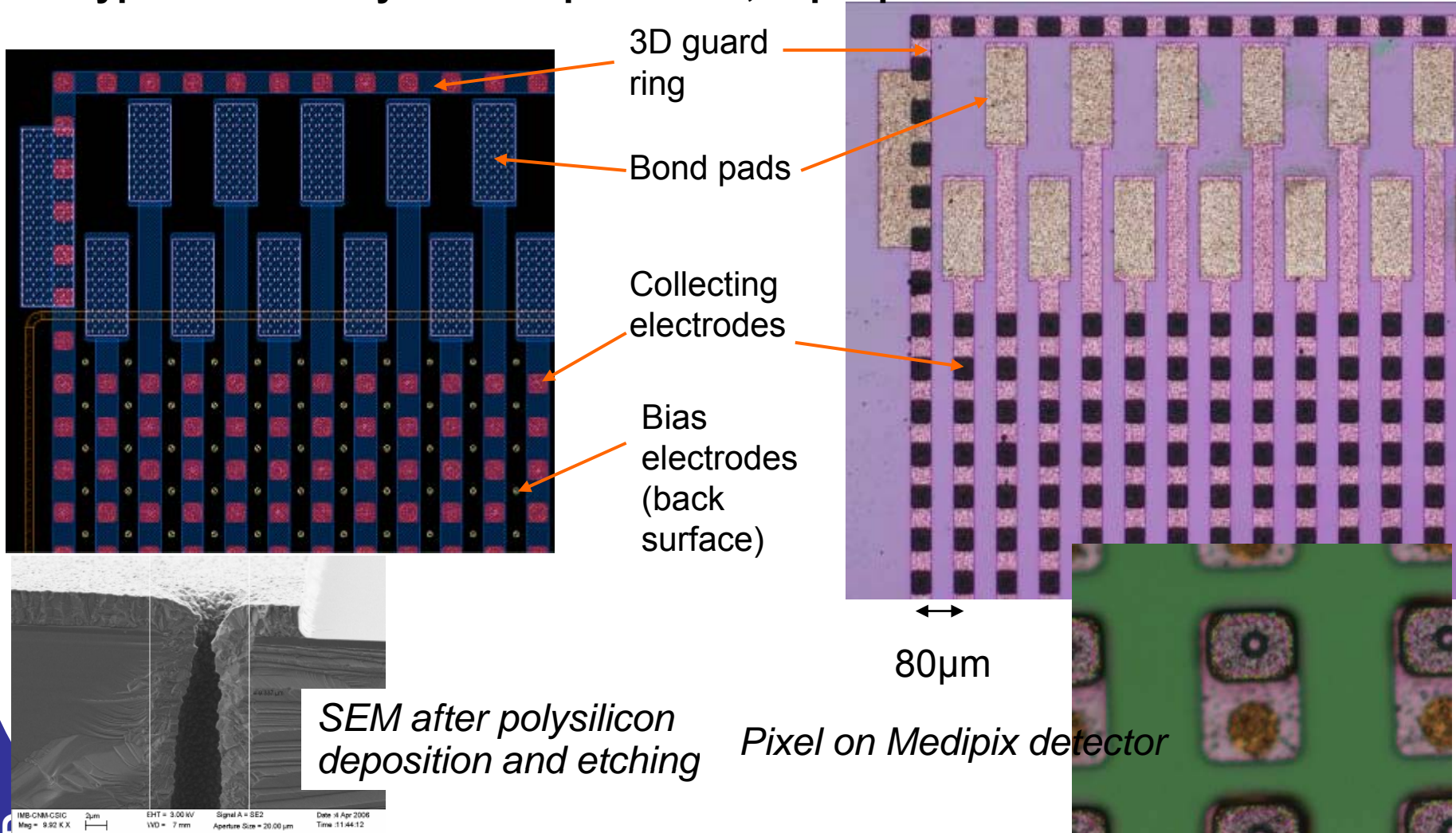


**3D**



# Finished 3D devices

Typical device layout – Strip detector, 80 $\mu$ m pitch



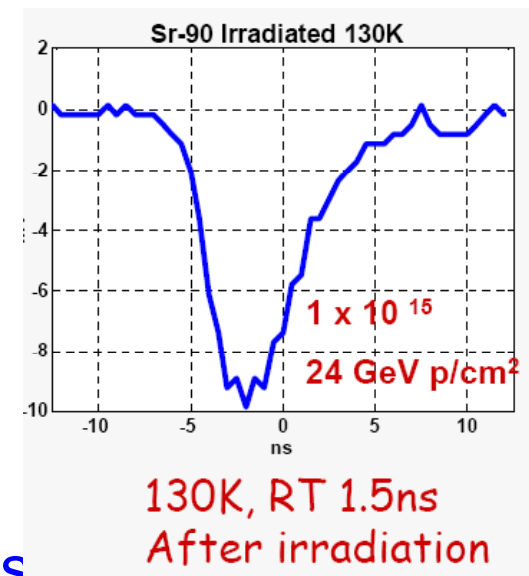
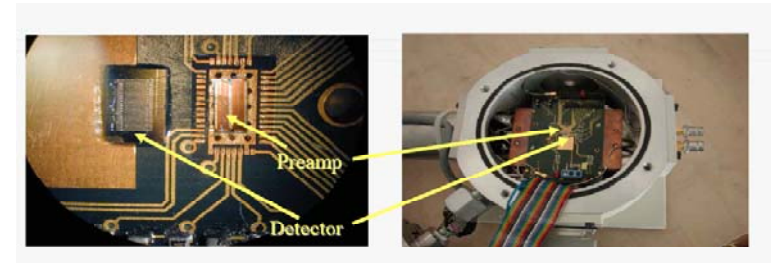
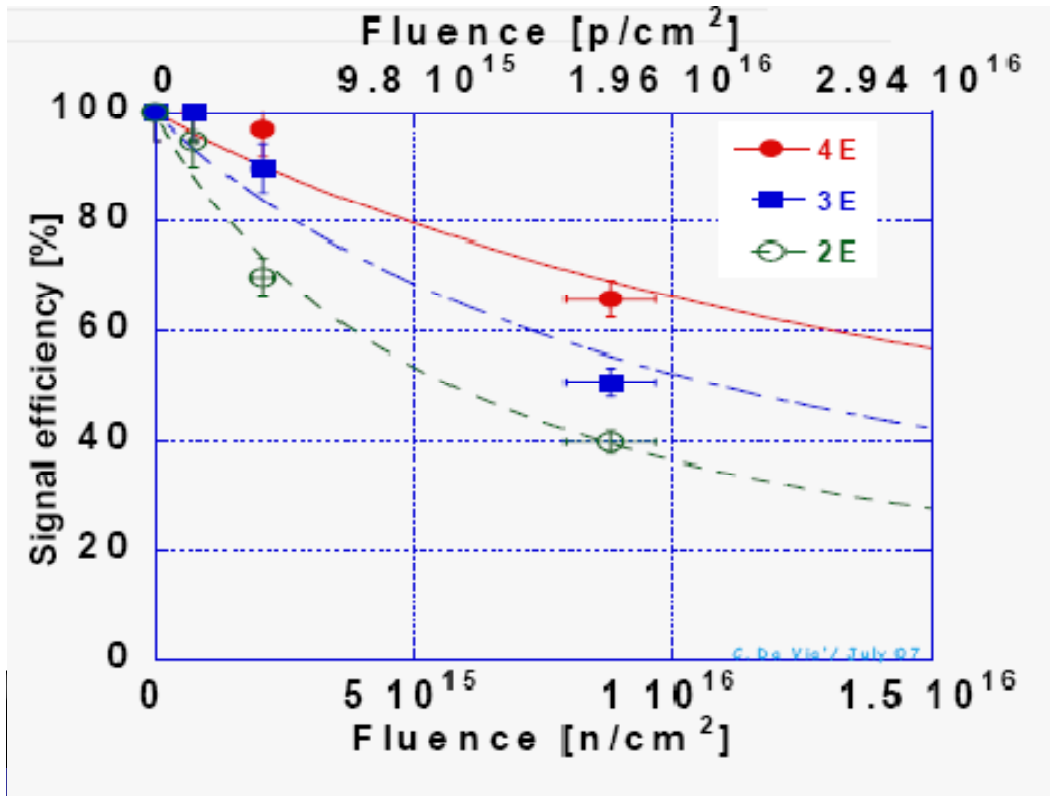
SEM after polysilicon deposition and etching

Pixel on Medipix detector

# Hawaii/Stanford/Manchester cont.

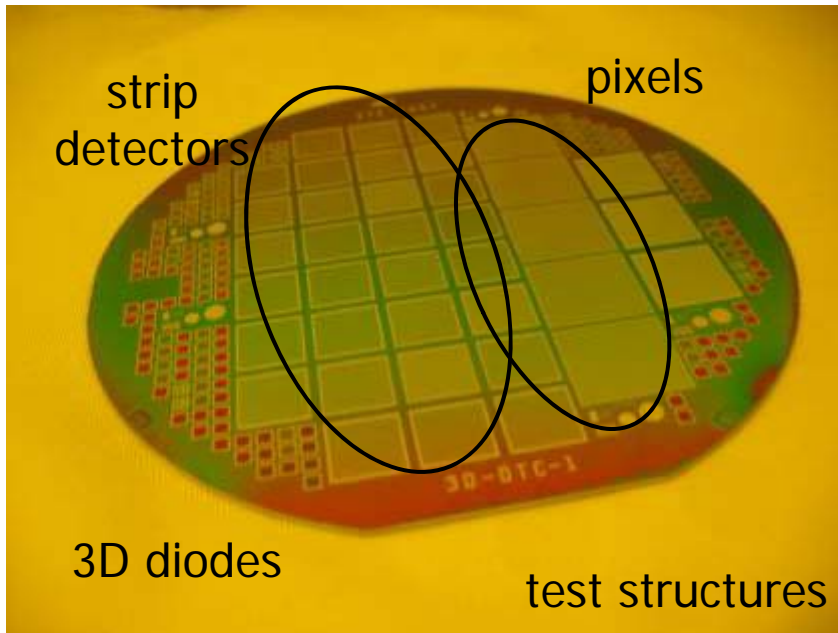
Stanford fabricated devices

- Fast timing applications
- FP220 in ATLAS trigger

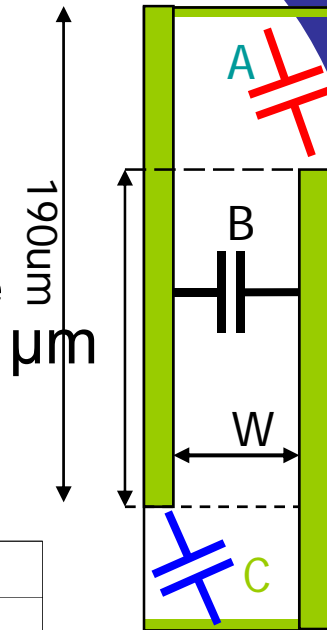


- Most advanced radiation results
- Results for different pixel configurations

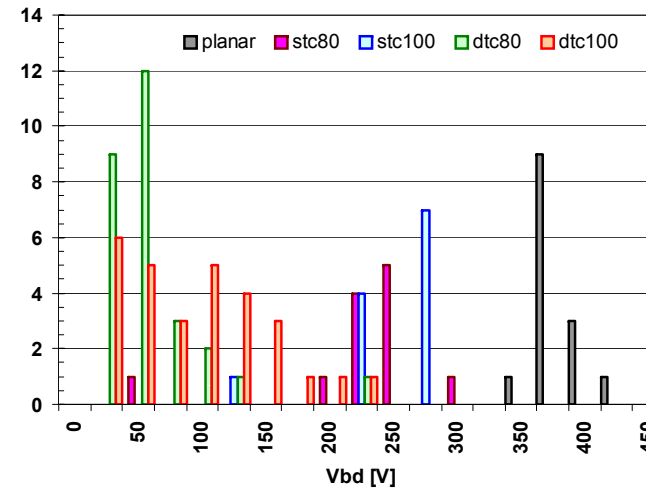
# FBK (Trento)



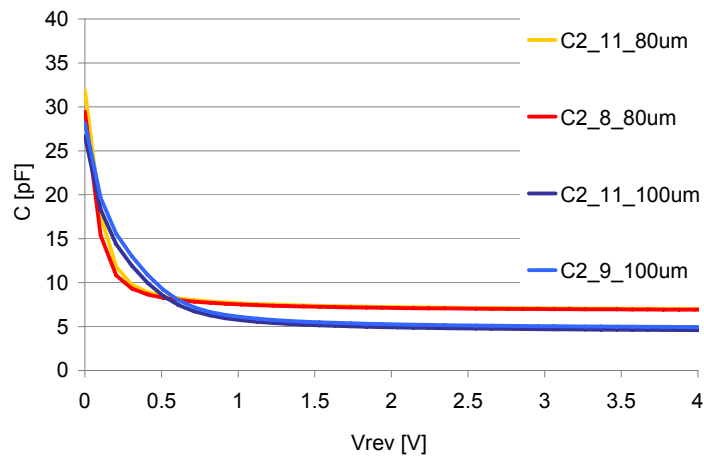
- Single Sided Single Type
- Double sided double type
  - First batch made
  - Depleted **2V**



Breakdown distribution



## Double sided double type



**Tested in CMS testbeam last week**  
 Panja Luukka, Helsinki, Uli Parzefall, Freiburg

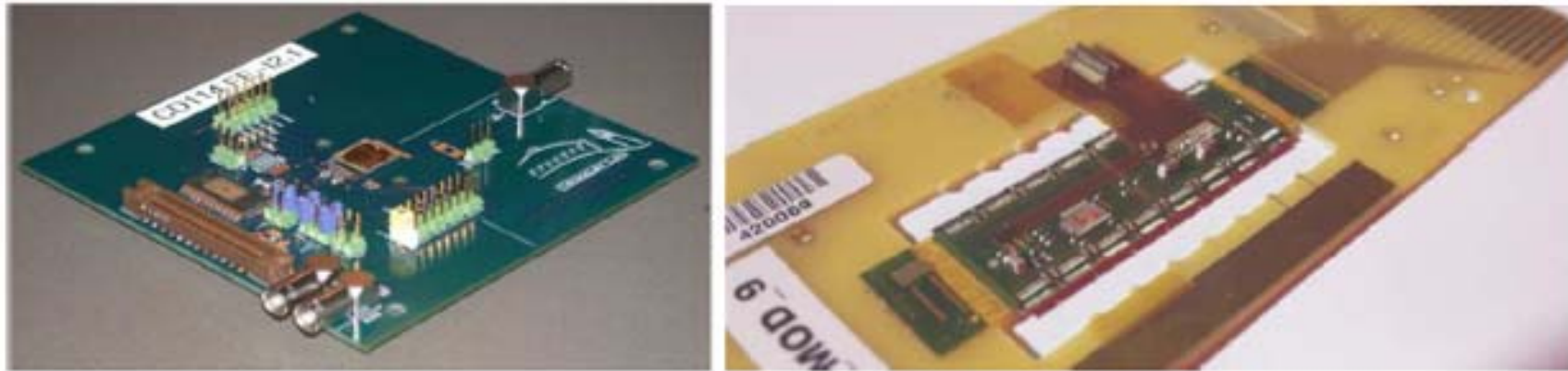
## 3D Summary

- 2008: the year 3D moved from hand-crafted to IKEA-rised ?
  - Double sided 3D detectors
  - (semi) commercial fabrication
- 3D strip detectors
- 3D pixel detectors
- **rad hard:** mm to cm from SLHC beam
- **Reduced charge sharing, edgeless**



# Diamond

## *ATLAS diamond pixel modules*



- ◆ Single chip and full modules bump-bonded at IZM (Berlin), constructed and tested in Bonn
- ◆ Operating parameters: Noise  $140e$ , Threshold  $1450-1550e$ , Threshold Spread  $25e$ , Overdrive  $800e$

# Diamonds

## ◆ Further Progress in Charge Collection

300  $\mu\text{m}$  collection distance diamond attained in wafer growth  
FWHM/MP  $\sim 0.95$  – Working with manufacturers to increase uniformity  
scCVD - Full charge collection, fast, large signals, Getting larger?  
New manufacturers

## ◆ Radiation Hardness of Diamond Trackers

Using trackers allows a correlation between S/N and Resolution  
With Protons:

- Dark current decreases with fluence
- $E=1\text{V}/\mu\text{m}$ : 15% S/N loss at  $2.2 \times 10^{15}/\text{cm}^2$ , 33% signal at  $1.8 \times 10^{16}/\text{cm}^2$
- pCVD and scCVD have same damage curve

## ◆ Diamond Pixel Detectors

Successfully tested a complete ATLAS module and scCVD module

- Excellent correlation for both between telescope and pixel data - stable op

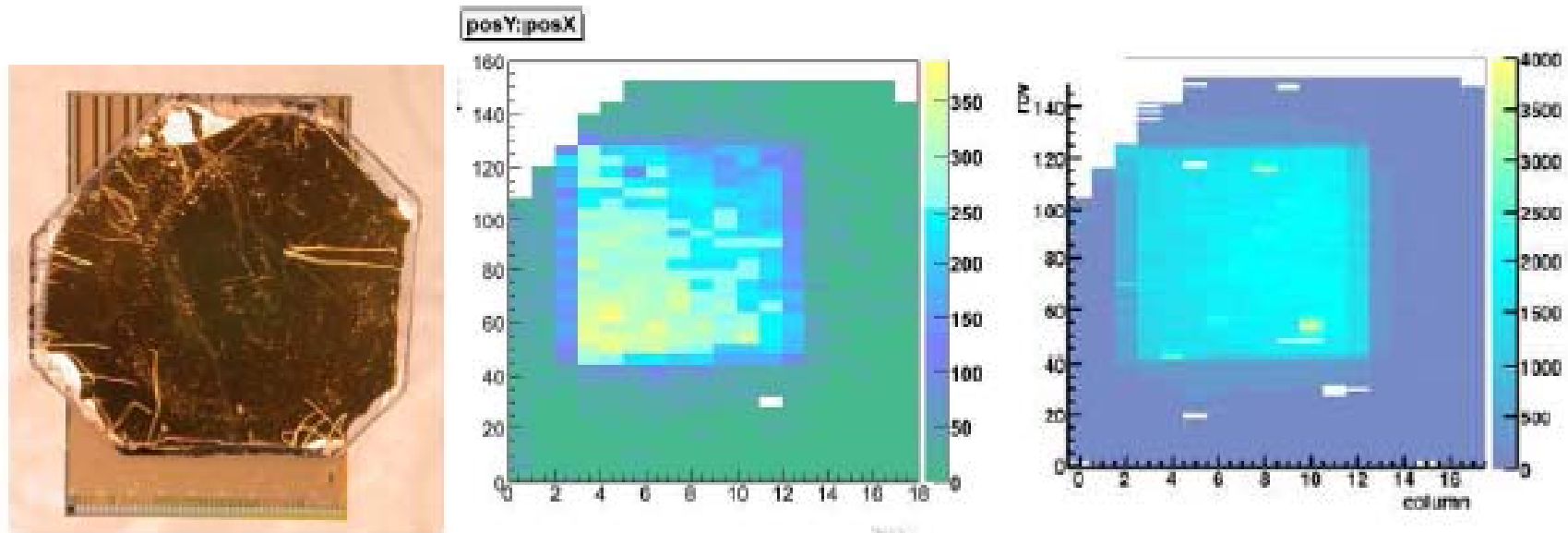
Diamond R&D Approved by ATLAS for LHC Upgrade R&D

## ◆ Beam Conditions Monitoring



# scCVD pixel

*The First scCVD ATLAS diamond pixel detector*



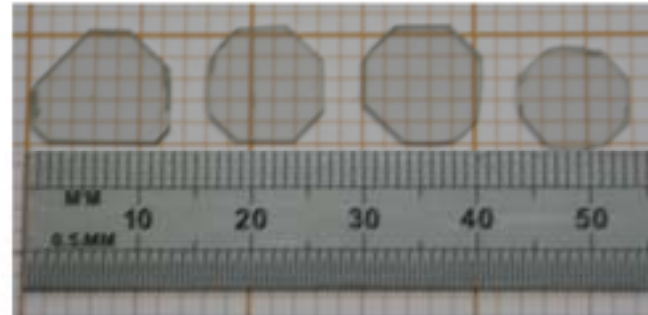
- ◆ The hitmap plotted for all scintillation triggers with trigger in telescope.
- ◆ The raw hitmap looks goods -  $\sim 1$  dead pixel



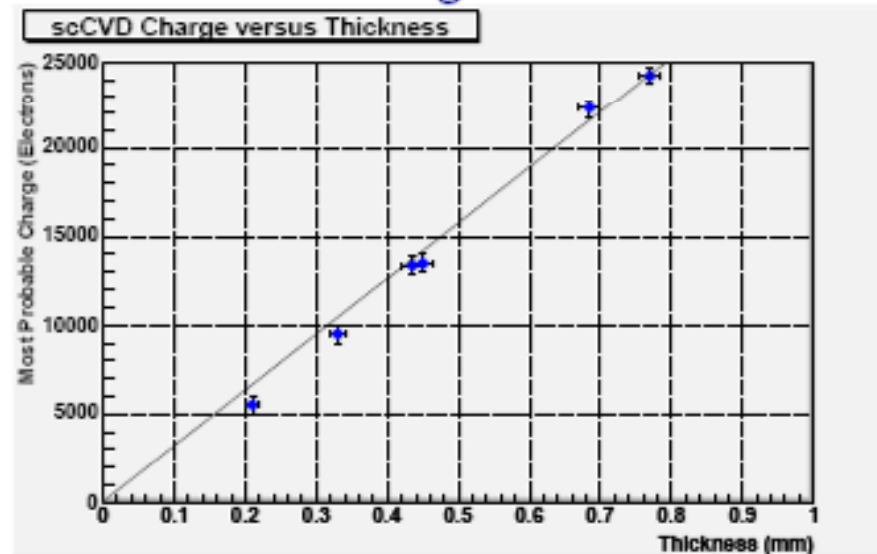
## Material Status - Single Crystal CVD Diamond



### Recent Single Crystal CVD Diamond

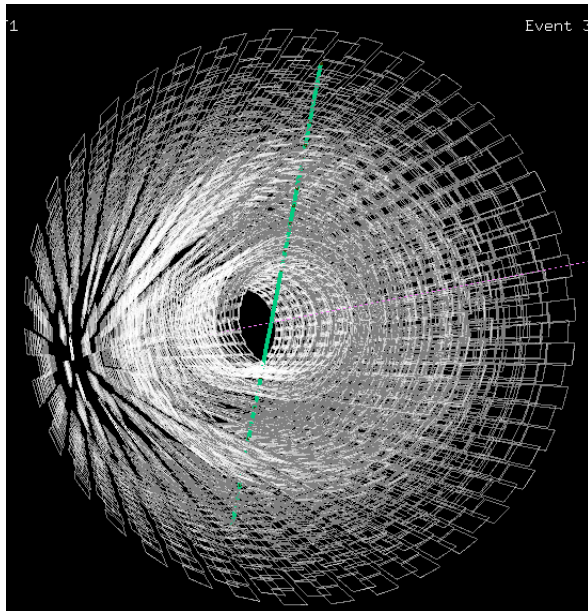


### scCVD Diamond Most Probable Charge versus Thickness



◆ High quality scCVD diamond can collect full charge for thickness  $880\mu\text{m}$

# CMS



Weakest point in present system is amount of material

Electron & photon conversions

Hadronic interactions

# Future power estimates

- Some extrapolations assuming 0.13 $\mu\text{m}$  CMOS
  - Pixels 58 $\mu\text{W}$  -> 35 $\mu\text{W}/\text{pix}$ 
    - NB sensor leakage will be significant contribution
  - Outer Tracker: 3600  $\mu\text{W}$  -> 700 $\mu\text{W}/\text{chan}$ 
    - Front end 500 $\mu\text{W}$  (M Raymond studies)
    - Links 170 $\mu\text{W}$  (including 20% for control)
  - PT layers: 300 $\mu\text{W}/\text{chan}$  - most uncertain
    - Front end 50 $\mu\text{W}$  (generous extrapolation from pixels)
    - Links 100 $\mu\text{W}$  (including 20% for control)
    - Digital logic 150 $\mu\text{W}$  (remaining from 300 $\mu\text{W}$ )
    - 100 $\mu\text{m}$  x 2.5mm double layer at  $R \approx 25\text{cm}$  => 11kW
- More detailed studies needed
  - sensor contribution not yet carefully evaluated
  - internal power distribution will be a significant overhead

# Power delivery

- Perhaps the most crucial question
  - although estimates of power are still imprecise, overall requirements can be estimated
  - we must reduce sensor power with thin sensors
    - finer granularity should allow adequate noise performance
  - and attempt to limit channel count to minimum compatible with tracking requirements (simulations!)
- total readout power expected to be ~25-35kW
  - in same range as present system so larger currents required
- Radical solutions required
  - serial powering or DC-DC conversion
  - neither are proven and many problems remain to be solved

# Comment

- Reducing power/pixel/strip is a good feature of reduced processing sizes
- But increasing density of pixels/strips increases the density
  - Supply of power and hence requirement of cooling and minimizing mass is now limiting designs

# P-type / ATLAS

- $p$ -type detectors most natural solution for  $e$  collection on segmented side
- $n$ -side read out  $\rightarrow$  lower collection time
- No type inversion
- No backplane processing
- Easier to handle (no need to take care of special gluing on the backside due to the presence of guard-rings. Possibility of operating under-depleted before irradiation)



*....and, up to 60% discount with respect to ...  
in-n!*

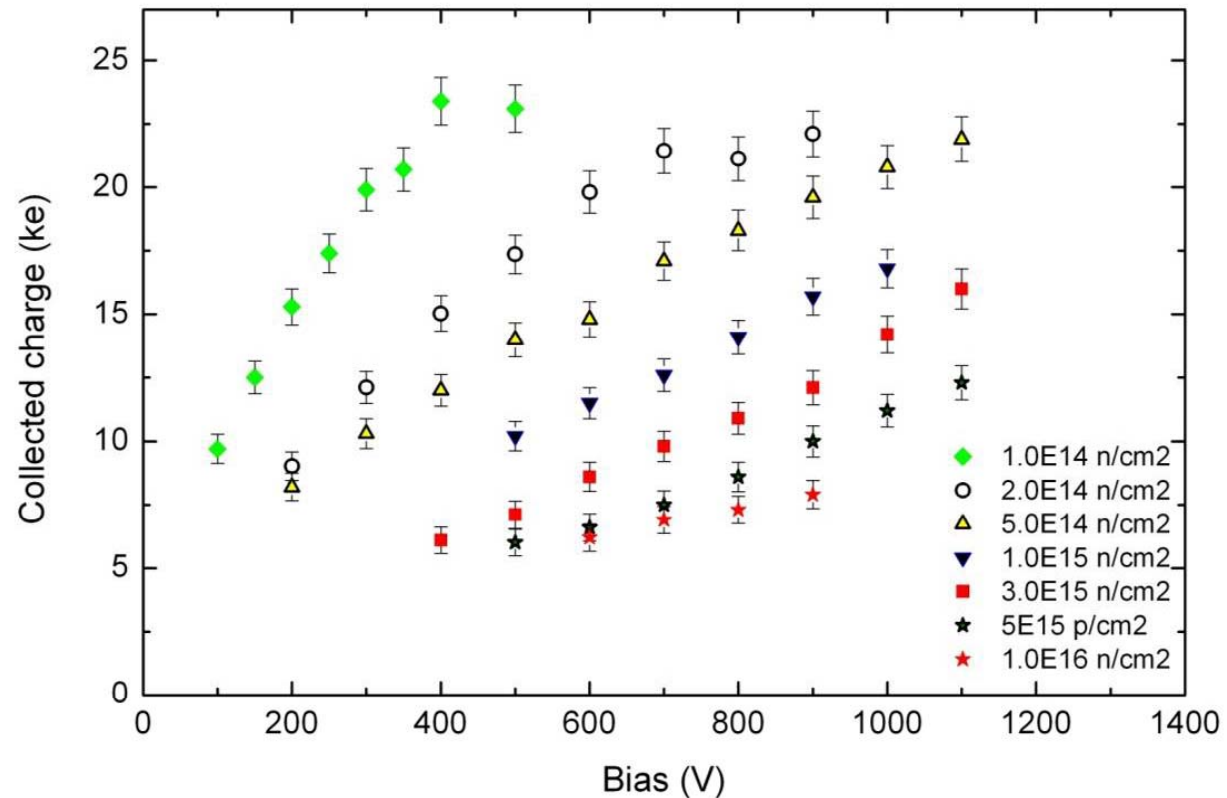
- Thin wafers easier

# Results

Outstanding results achieved: studies of charge collection of irradiated detectors pushed to  $1 \times 10^{16} \text{ n cm}^{-2}$ .

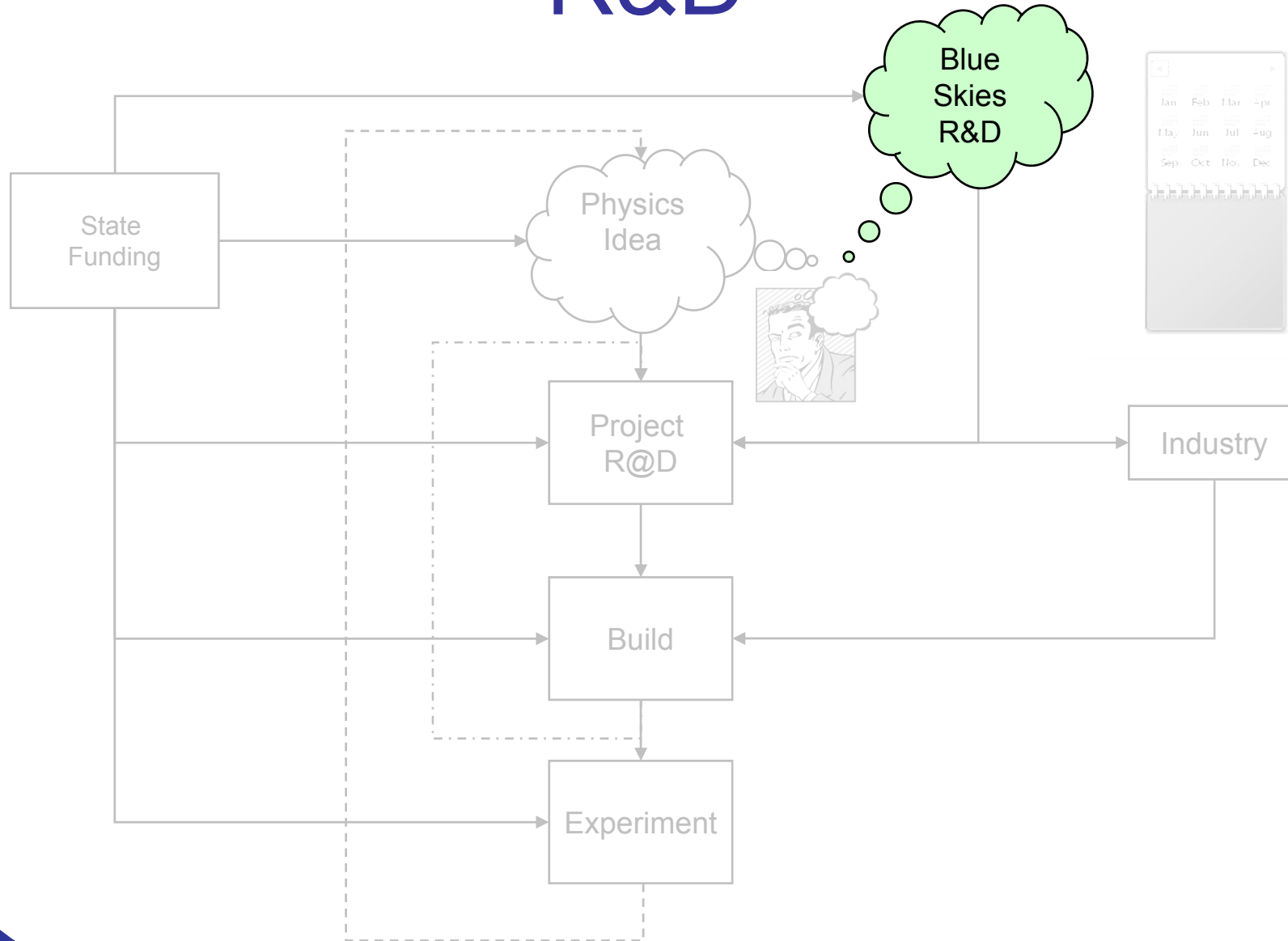
Prel. results at  $1.5 \times 10^{16} \text{ n cm}^{-2}$  available.

Significant signal even after these very high doses.





# R&D

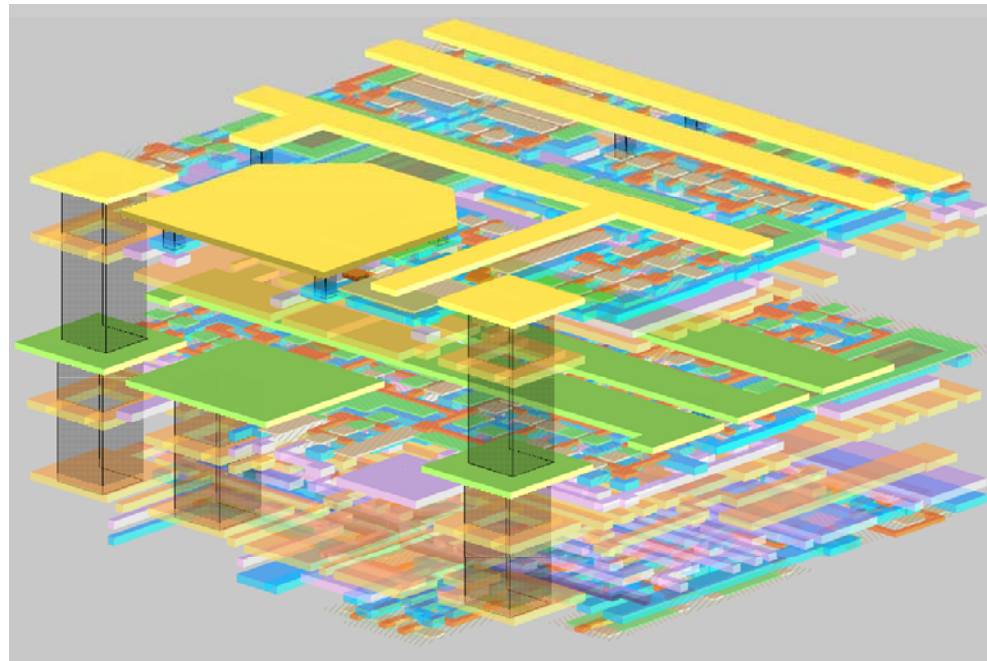


# Driving forces

- Future experiments ILC
  - But also Belle Upgrades
  - Super-B etc
- High resolution
- Low mass
- Radiation tolerance
- Speed

# Vertical Integration

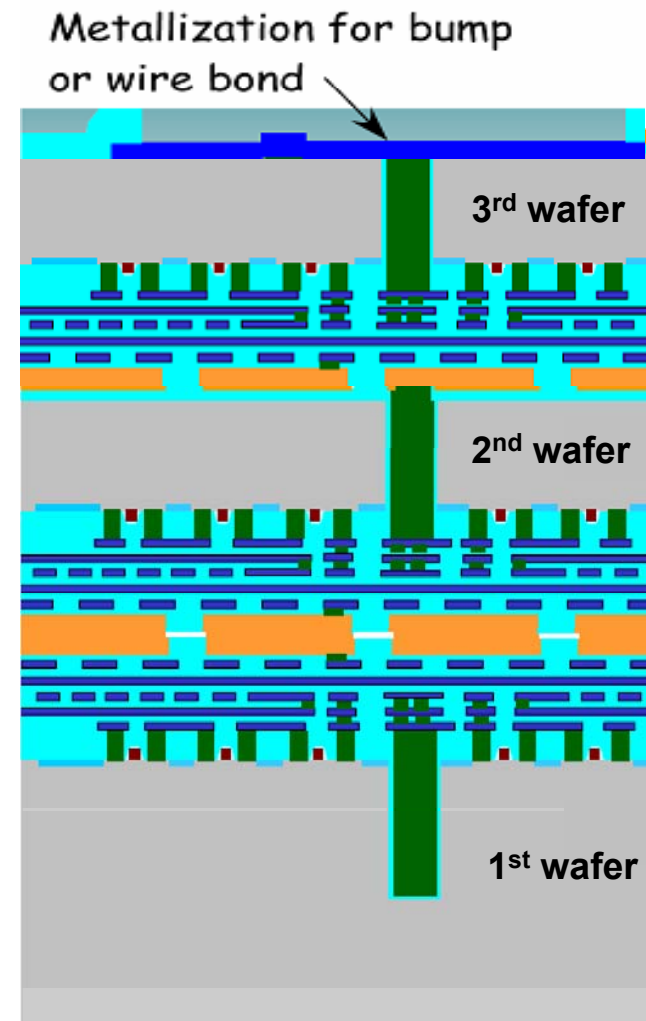
- This has been a “dream” for many years
- More complex detectors, low mass
- Liberate us from bump/wire bonding



## 3D integration plans with commercial vendors

### - Advantages of the Tezzaron/Chartered process:

- ▶▶ No extra space allotment in BEOL for 3D TSV,
- ▶▶ 3D TSVs are very small, and placed close together,
- ▶▶ Minimal material added with bond process,
- ▶▶ 35% coverage with 1.6  $\mu\text{m}$  of Cu =>  $X_o=0.0056\%$ ,
- ▶▶ No material budget problem associated with wafer bonding,
- ▶▶ Advanced process 0.13  $\mu\text{m}$  and below
- ▶▶ Good models available for Chartered transistors,
- ▶▶ Thinned transistors have been characterized,
- ▶▶ Process supported by commercial tools and vendors,
- ▶▶ Fast assembly + Lower cost (12 3D processed wafers @ \$250k in 12 weeks),

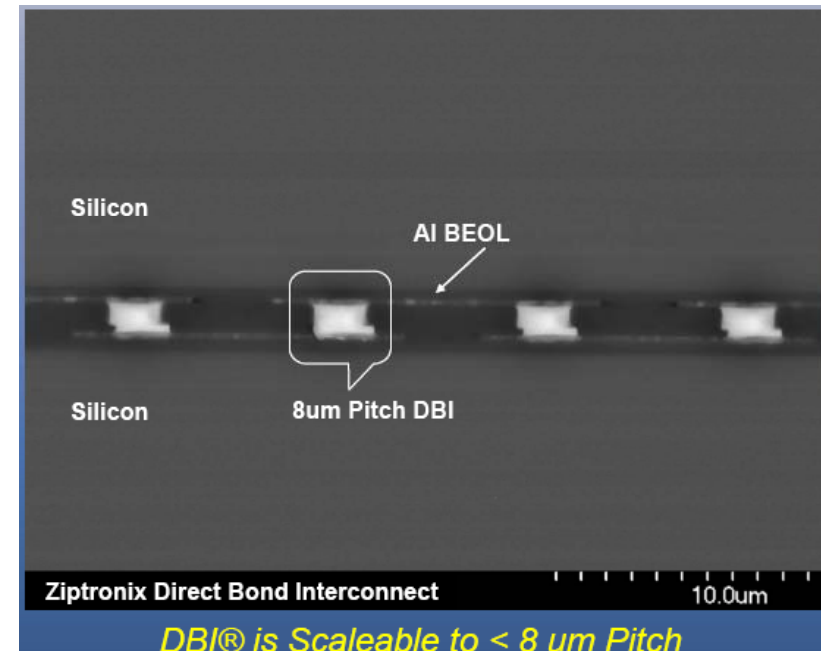


## 3D integration plans with commercial vendors

- Another demand for 3D assembly comes from detector/ROIC bonding; Fermilab is working with **Ziptronix** to do low mass bonding with DBI to detectors. (FPIX chips to 50 um thick sensors.);
- Conventional solder bumps or CuSn can pose a problem for low mass fine pitch assemblies

**Ziptronix** - uses Direct Bond Interconnect (oxide bonding)

- Ziptronix is located in North Carolina
- Fermilab has current project with Ziptronix to bond BTEV FPIX chips to 50 um thick sensors.
- Orders accepted from international customers



# Vertical Integration

- **3D Integration is very attractive for highly granular detector systems,**
- **Bonding is low temperature process, adds limited amount of high-Z material,**
- **3D-Integration may extend use of certain detector type (MAPS),**
- **3D-Integration is starting to be available in industry,**
- **Will our community be able to afford?**

# Other detectors concepts

- CCDs
- MAPS and DNW
- DEPFETs
- CMOS+SOI

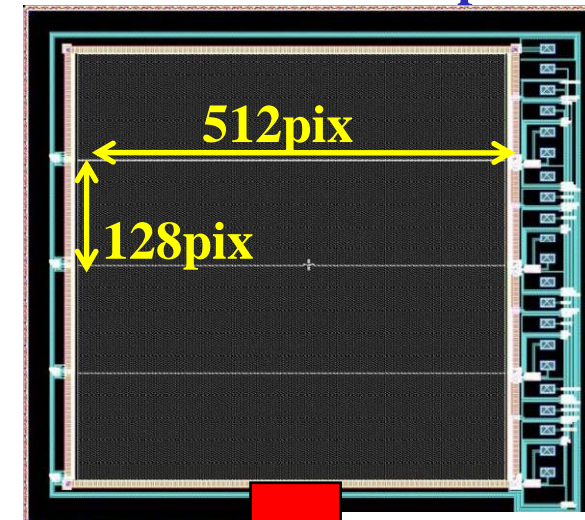
# FPCCD

The test-sample of FPCCD was produced in Mar., 2008 by Hamamatsu.

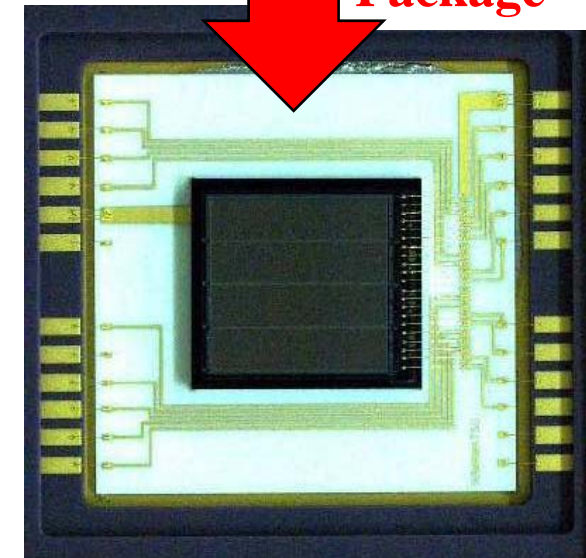
## FPCCD test-sample

- Chip-size :  $8.2 \times 7.5 \text{ mm}^2$
- Pixel size:  $12 \times 12 \mu\text{m}^2$
- # of readout channels: 4
  - $512 \times 128 \text{ pix/ch}$
- The several combinations of the wafer-thickness and amplifier-types were produced.
  - Wafer thickness (epi) :  $15\mu\text{m}$ ,  $24\mu\text{m}$ 
    - ✓  $24\mu\text{m}$ -ware has higher specific resistance for easy full-depletion.
  - Amplifier : 7 types

FPCCD test-sample



Package





# MAPS R&D

- Proof of principle (APSEL0-2)
  - first prototypes realized in 130 nm triple well ST-Micro CMOS process
- APSEL3
  - 32x8 matrix with sparsified readout
  - Pixel cell optimization (50x50  $\mu\text{m}^2$ )
    - Increase S/N (15 $\rightarrow$ 30)
    - reduce power dissipation x2
- APSEL4D
  - 4K(32x128) pixel matrix with data driven sparsified readout and timestamp
  - Pixel cell & matrix implemented with full custom design and layout
  - Sparsifying logic synthesized in std-cell from VHDL model
  - Periphery includes a “dummy matrix” used as digital matrix emulator
- Test Beam foreseen in Sep 2008
  - Prototype MAPS module + stripets

PSD

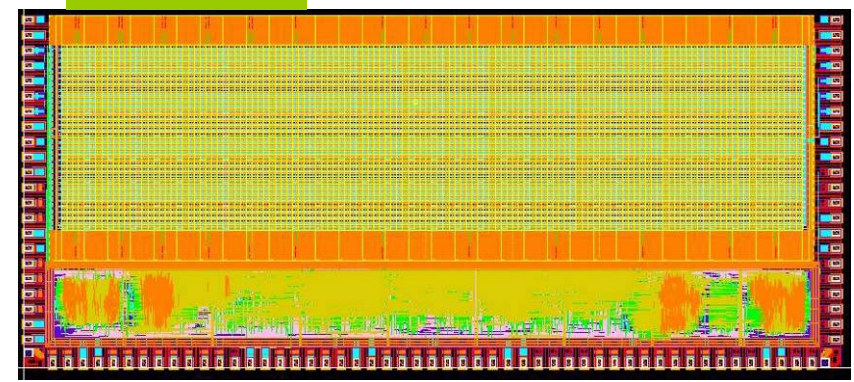


## Submitted MAPS Chips

Sub. 12/2004 TEST_STRUCT	Sub. 8/2005 APSELO	Sub. 8/2005 APSEL1	Sub. 8/2006 APSEL2M	Sub. 8/2006 APSEL2T	Sub. 9/2006 APSEL2_90
ST 130 Process characterization	Preamplifier characteriz.	Improved F-E 8x8 Matrix	Cure thr disp. and induction	Accessible pixel Study pix resp.	ST 90nm characterization
Sub. 11/2006 APSEL2D	Sub. 5/2007 APSEL3_CT	Sub. 7/2007 APSEL3D	Sub. 7/2007 APSEL3_T1, T2		
Test digital RO architecture	Test chips for shield, xtalk	32x8 Matrix. Shielded pix. Test for final matrix	Test chips to optimize pixel and F-E layout		

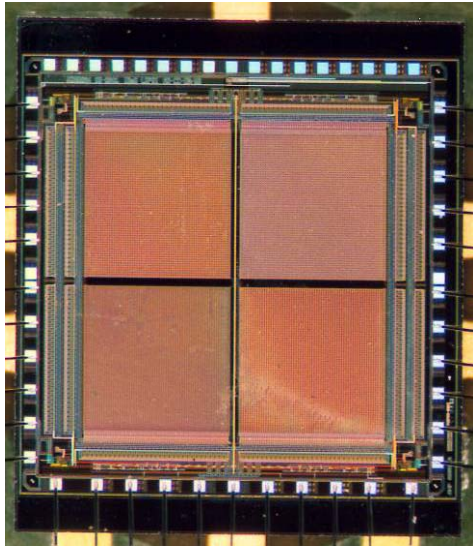
Sept 12, 2007 F.Forti - SLIM5 6

## APSEL4D sub 11/2007- rec 3/2008



32x128 4k pixel matrix for beam test

# CMOS-sensors (MAPS)



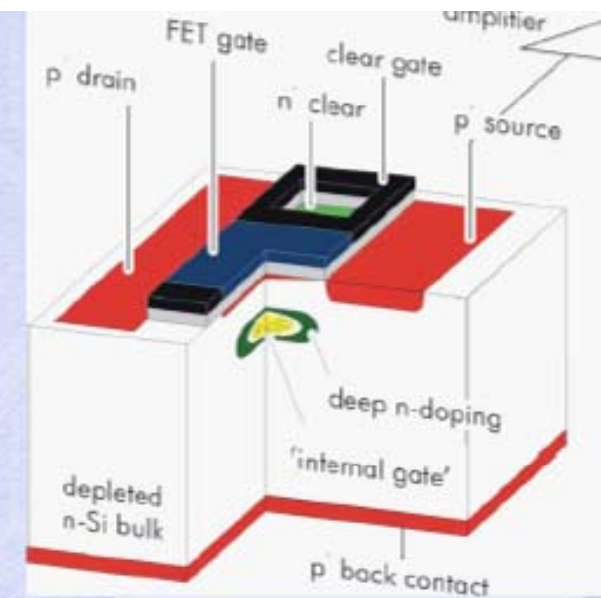
MIMOSA IV

## Features of the MIMOSA – detectors:

- Single point resolution  $1.5\mu\text{m} - 2.5\mu\text{m}$
- Pixel – pitch  $10 - 40 \mu\text{m}$
- Thinning achieved  $50 - 120\mu\text{m}$
- S/N for MIPs  $20 - 40$
- Radiation hardness:  $1\text{MRad} ; 1 \times 10^{13} \text{ n}_{\text{eq}}/\text{cm}^2$
- Time resolution  $\sim 20 \mu\text{s}$  (massive parallel readout)

# DEPFET

- . Intense R&D has been done for ILC pixel sensors  
has been used in several experiments already!
- . Technology is available in MPI only
- . Sensor size is limited by wafer size  
 $50\ \mu\text{m} \times 75\ \mu\text{m}$ : 215 x 512 pixel (adjustable)  
almost no gap in the acceptance
- . **Not very rad-hard** ( tested up to 1Mrad )  
OK up to 8Mrad??
- . Small power consumption
- . Reset switcher chip: Voltage swing > 8V
- . Thickness  $20\ \mu\text{m} \sim 100\ \mu\text{m}$  (adjustable for experiments)
- . Doubly-correlated sampling can be done  $\rightarrow$  low noise
- . 10kHz trigger rate, 0-suppression,  $\sim 4$ pixels/hit, 32 bits/pixel including address  
Disadvantage:  $\sim 1\%$  inefficiency
- . Data processing is done in subsequent chips  
on repeater system or in backend system



# A few thoughts

- Overestimate 5 year impact and underestimate 20 year impact
  - *Vertical Integration !*

# Last PSD 2005

## CONCLUSION

**R&D MUST BE AMBITIOUS**

**PREPARE ANSWERS TO FUTURE CHALLENGES** EVEN UNKNOWN

**USE INDUSTRY TRENDS in Si towards '3D'**

**R&D MUST INCLUDE SYSTEM ASPECTS**

**ON-LINE, OFF-LINE ANALYSIS**

**OTHER WORLD**

# 2008

- Massive Progress in many areas
  - 3D
  - CMOS devices (following industry)
  - n<sup>+</sup>p detectors
- Smörgåsbord of technological choices
  - Which ones will make it into detectors?
  - Practicality and COST!
  - How many can be used in non HEP applications?
- Commissioning of major LHC detectors
- Launch of LHC upgrades
  - Will this boost or stifle R&D?

# Summary

- R&D healthy and innovative
- Detectors builders worry about prosaic issues
  - Power
  - Cost
  - Material
- New paradigms on the horizon...
- PSD9 should be VERY exciting!